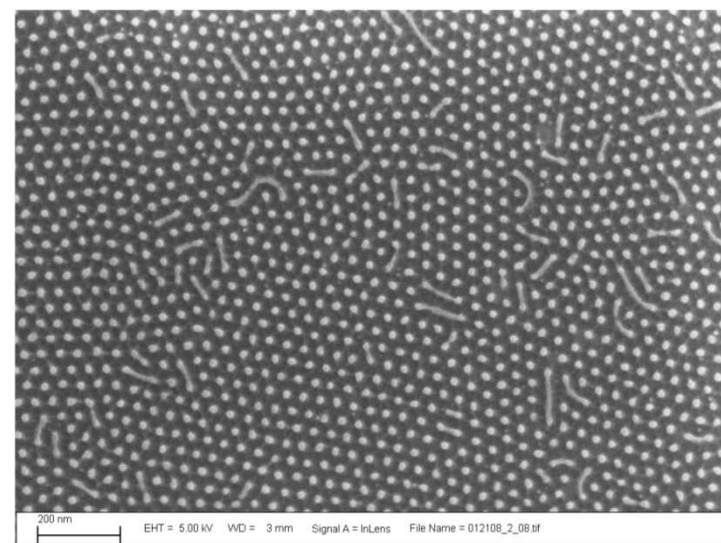
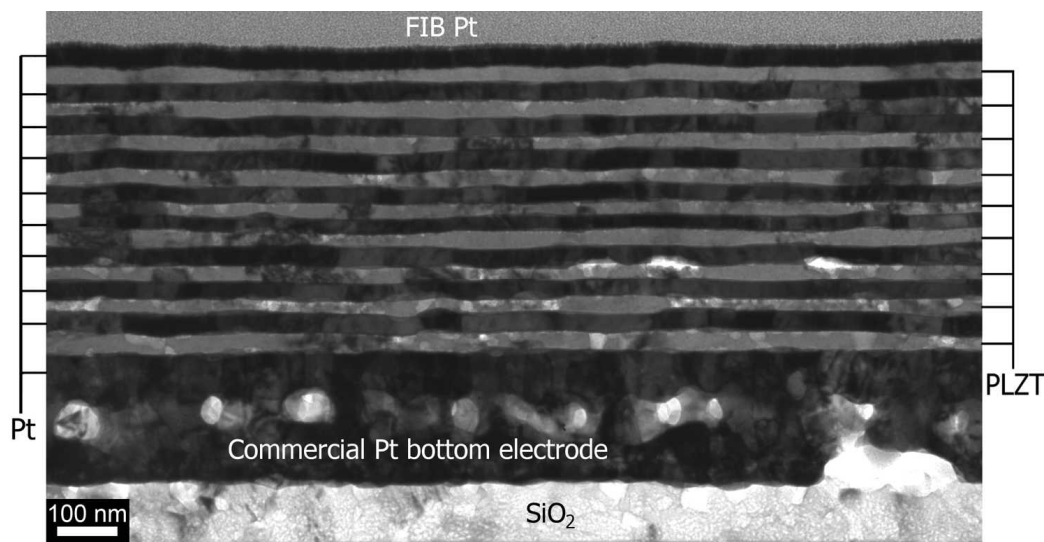


Functional Solution-Derived Nanoscale Electronic Oxides

Geoff Brennecka, J.S. Wheeler, C.M. Parish, and B.A. Tuttle
Sandia National Laboratories





Acknowledgments

Sandia

- Pat Mahoney
- Mark Rodriguez
- Christian Arrington
- Aaron Gin
- David Scrymgeour
- Bonnie McKenzie
- Michael Rye
- Jeff Stevens
- Jen Sigman
(now at Micron)

U. Texas - Austin

- John Ekerdt
- Sean Coffee
- Wyatt Winkenwerder

U. Wisconsin

- Paul Nealey
- Padma Gopalan
- Shengxiang Ji

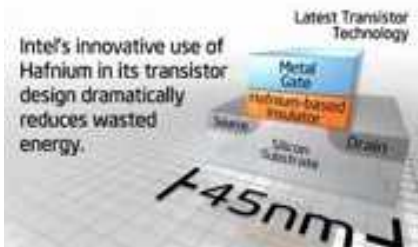
U. Florida

- Jacob Jones

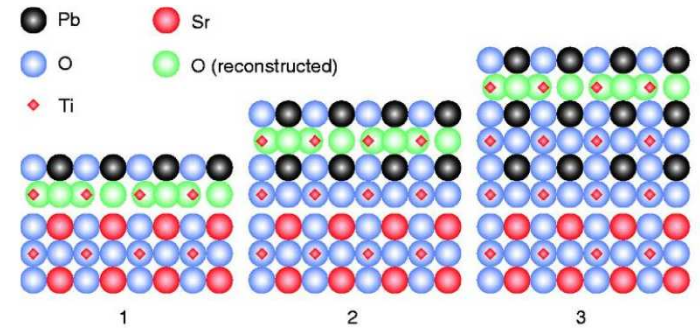
Background & Motivation



- Reduce physical size
- Increase function(s)
- Reduce power consumption

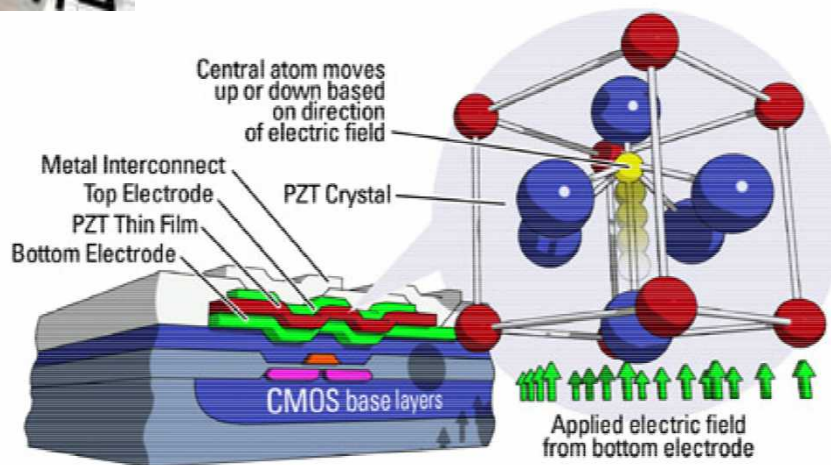


intel now using HfO_2 in their processors (45nm transistors)



Film Thickness (unit cells)

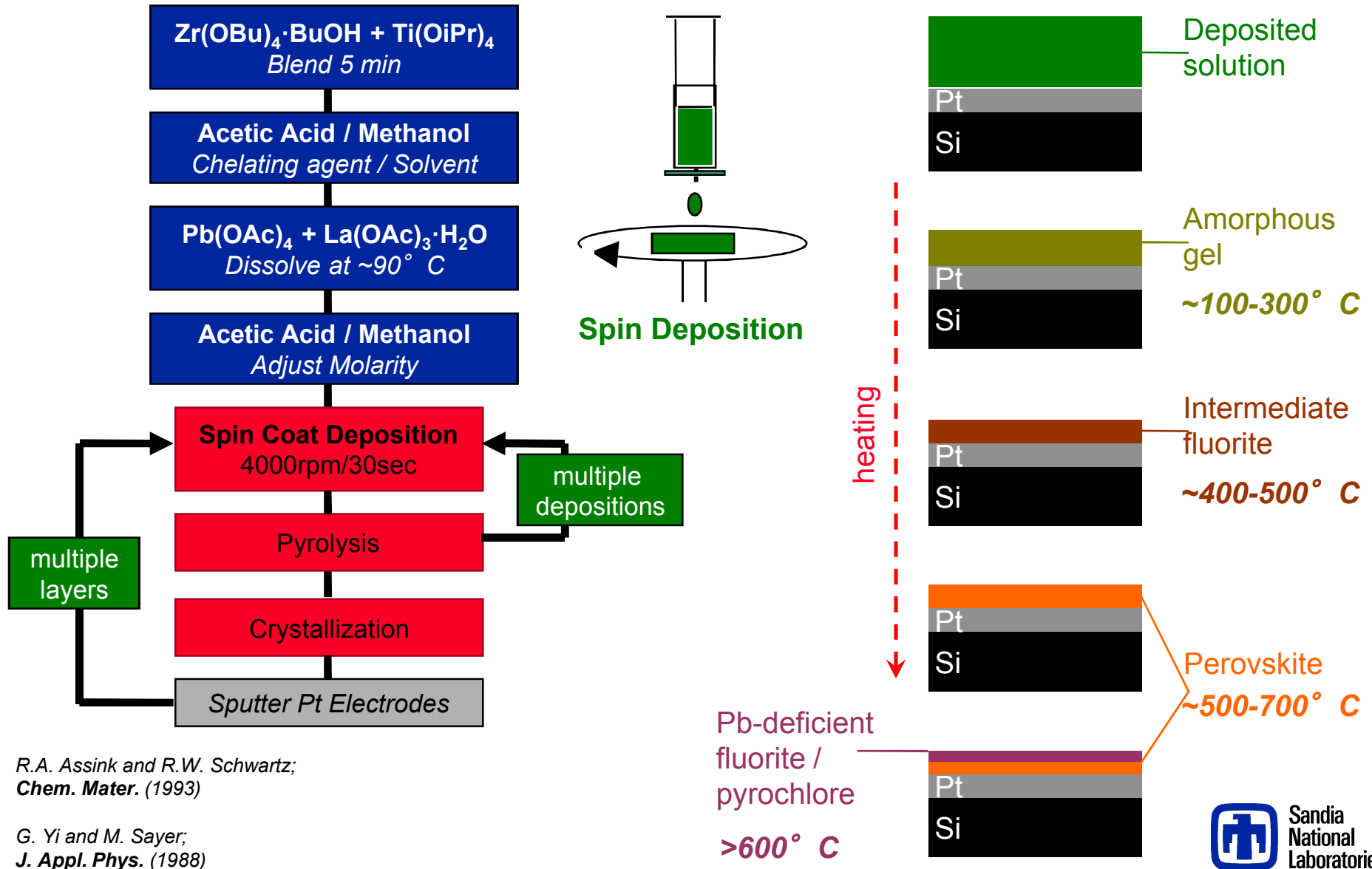
Fong et al., Science (2006)



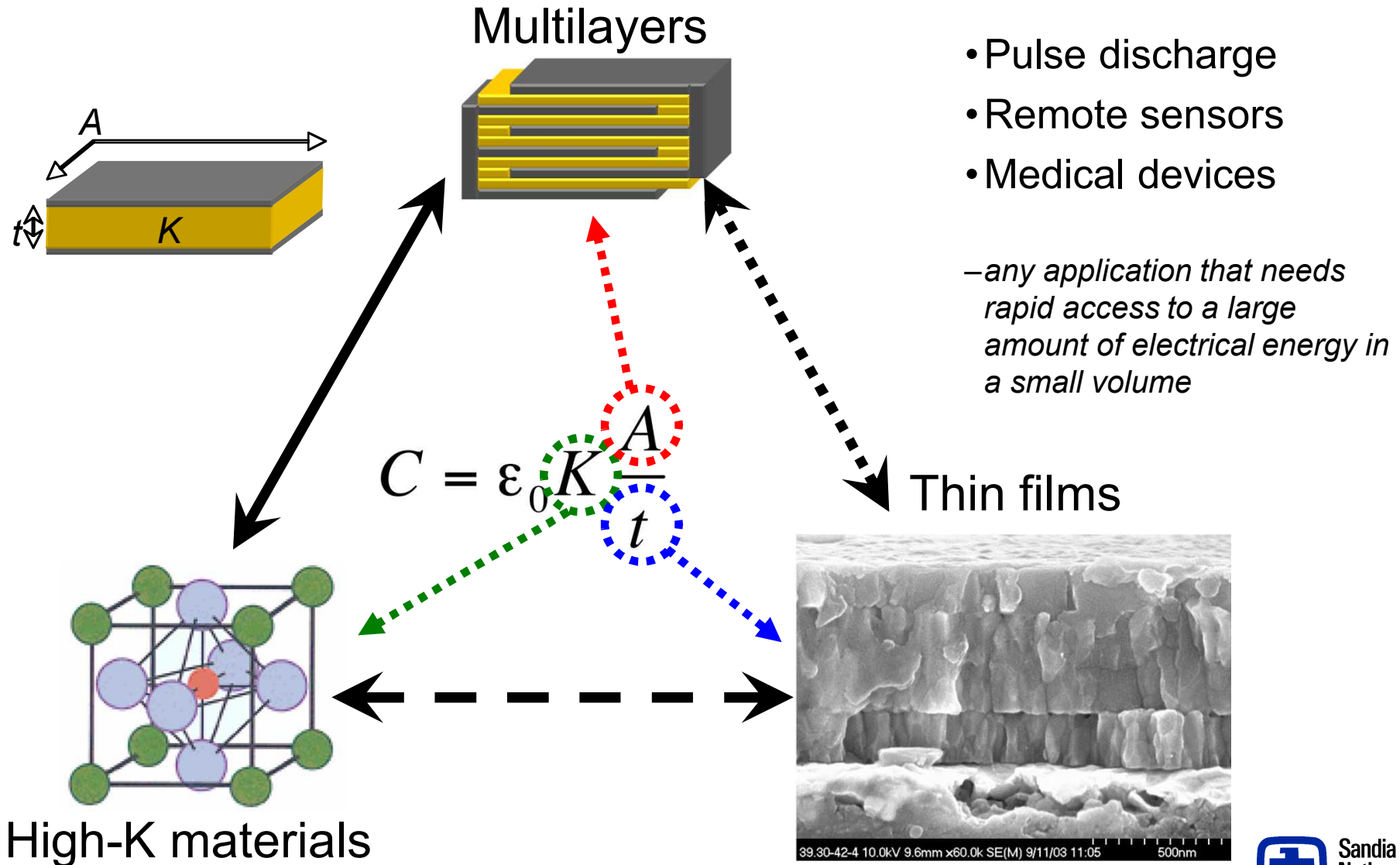
Ramtron FERAM

- Process/architecture
- Materials/integration

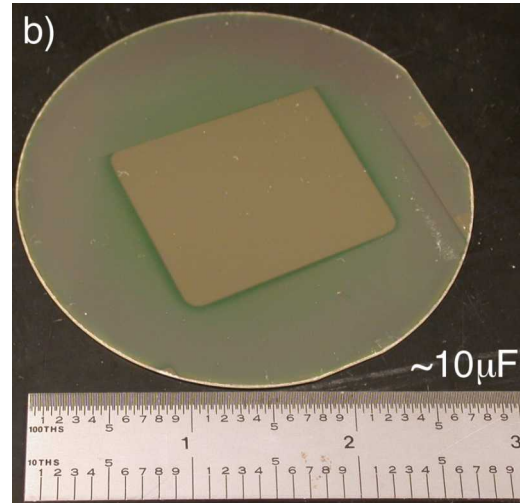
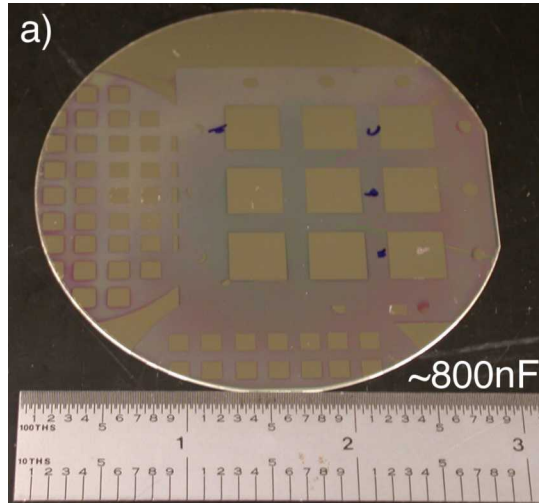
SNL 'IMO' Solution Route



High-Value Integrated Capacitors

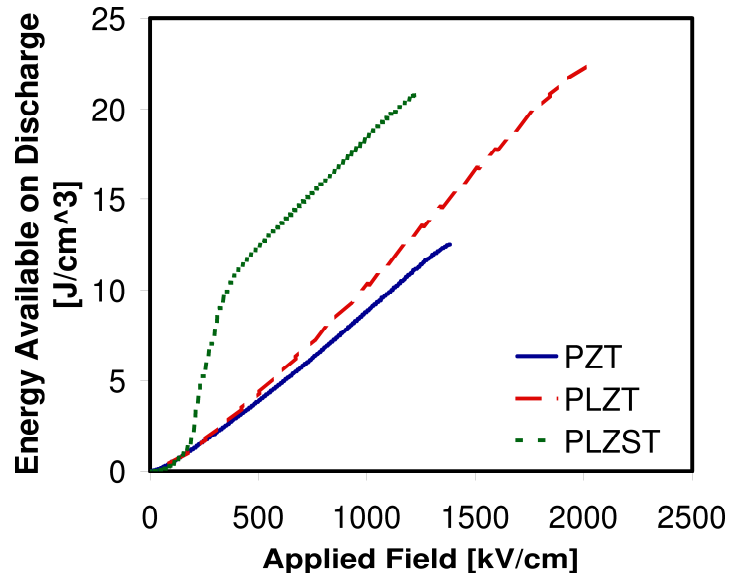


High Energy Density Pulse Discharge Capacitors

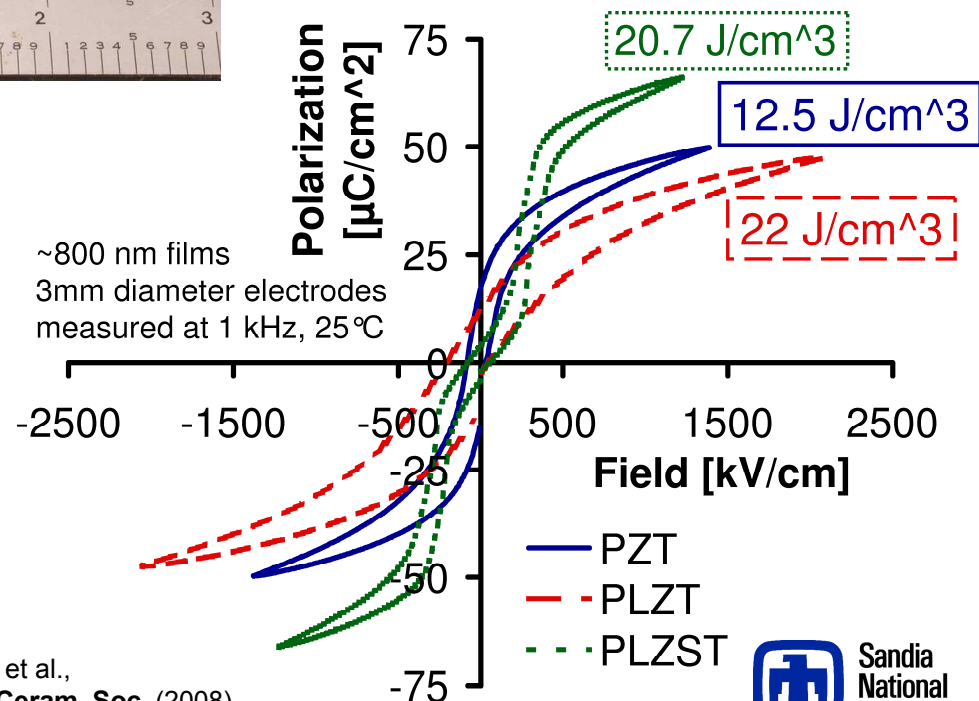


'Standard' thin films

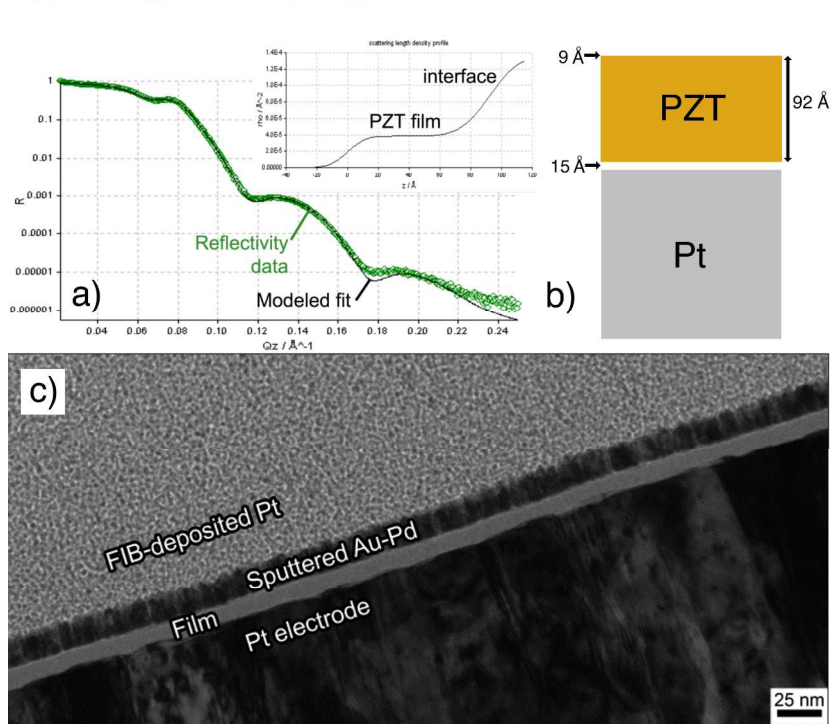
- ~250 - 1000nm thick
- applications >50V
- high energy density
- pulse discharge



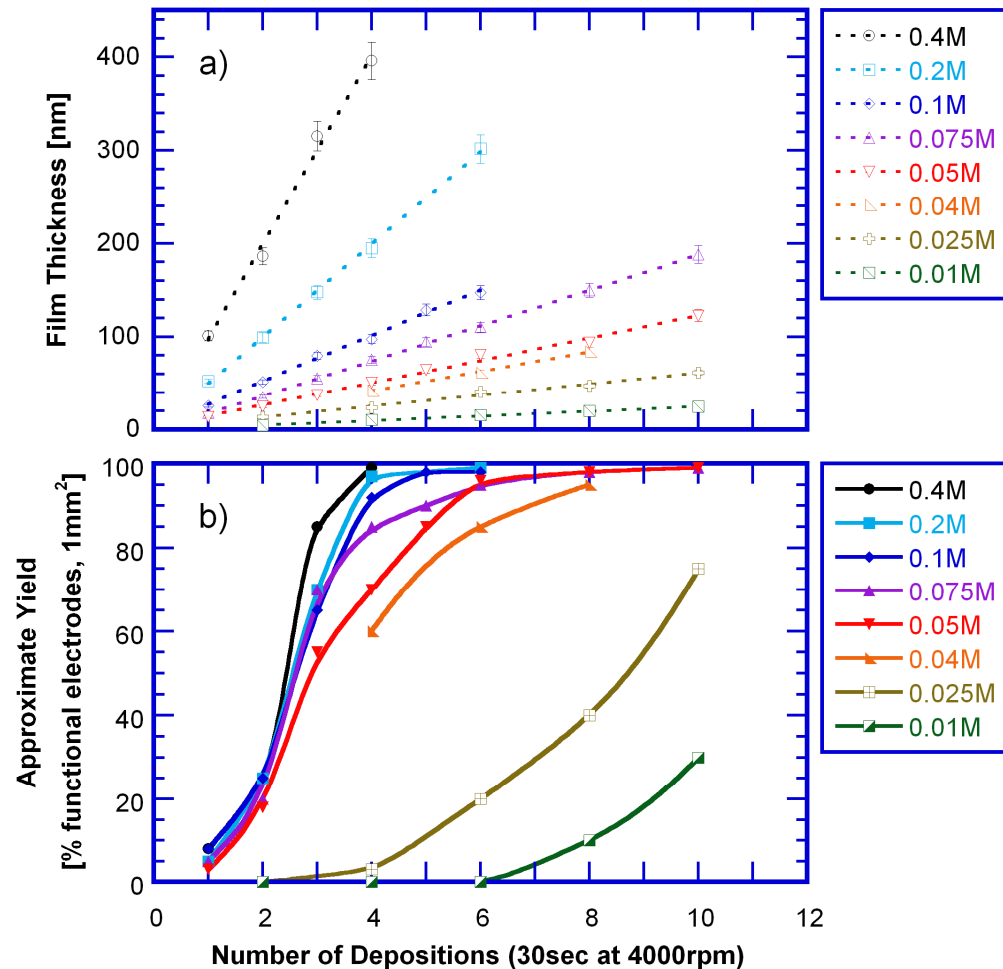
Sigman et al.,
J. Am. Ceram. Soc. (2008)



High Capacitance Ultrathin Films



- Single-phase continuous PZT films as thin as 9nm fabricated via spin coating
- Minimum thickness ultimately limited by islanding during crystallization



Sigman et al., *J. Am. Ceram. Soc.* (2008)
Brennecke, et al., *J. Mater. Res.* (2007)

Multilayer Structures

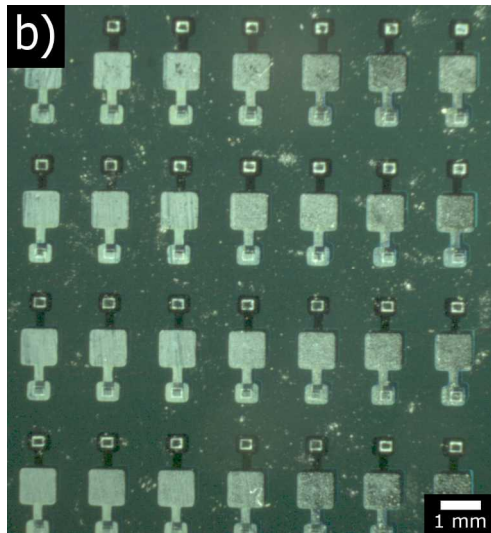
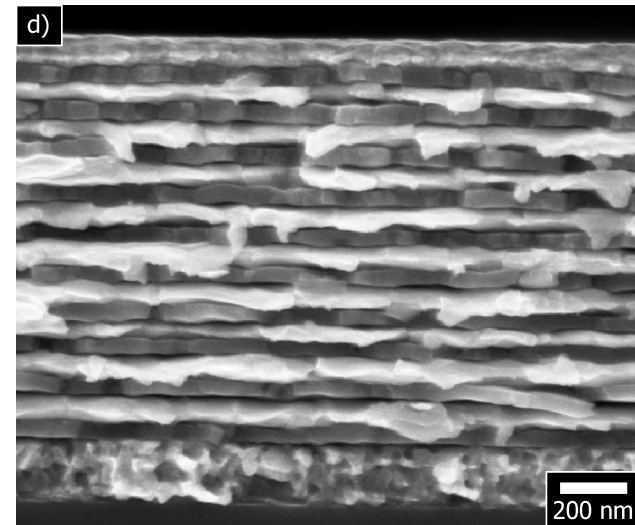
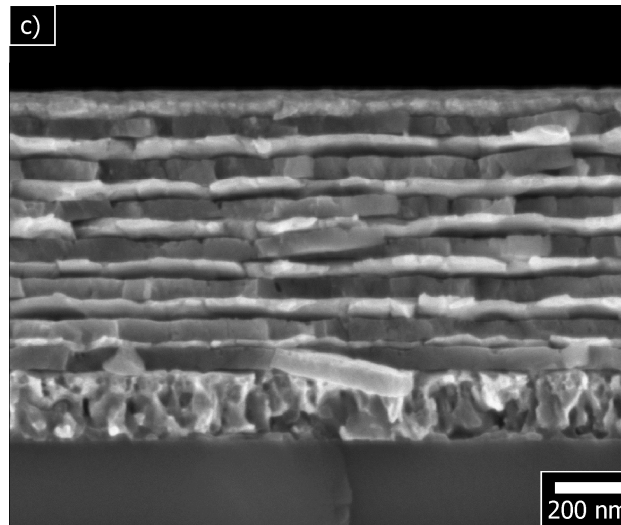
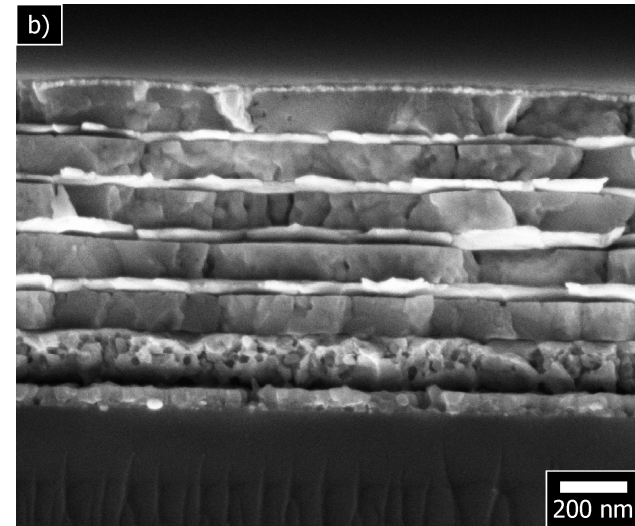
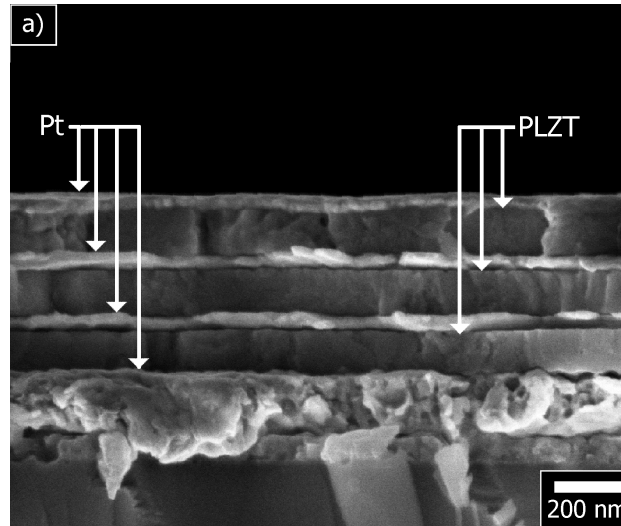
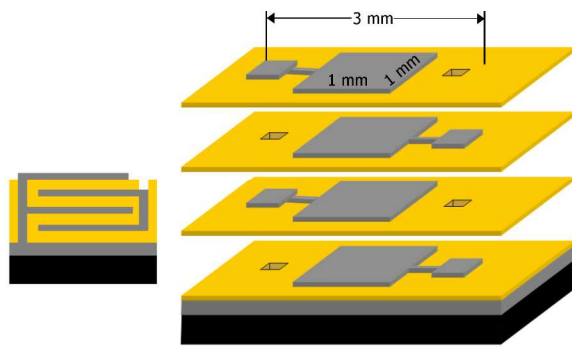
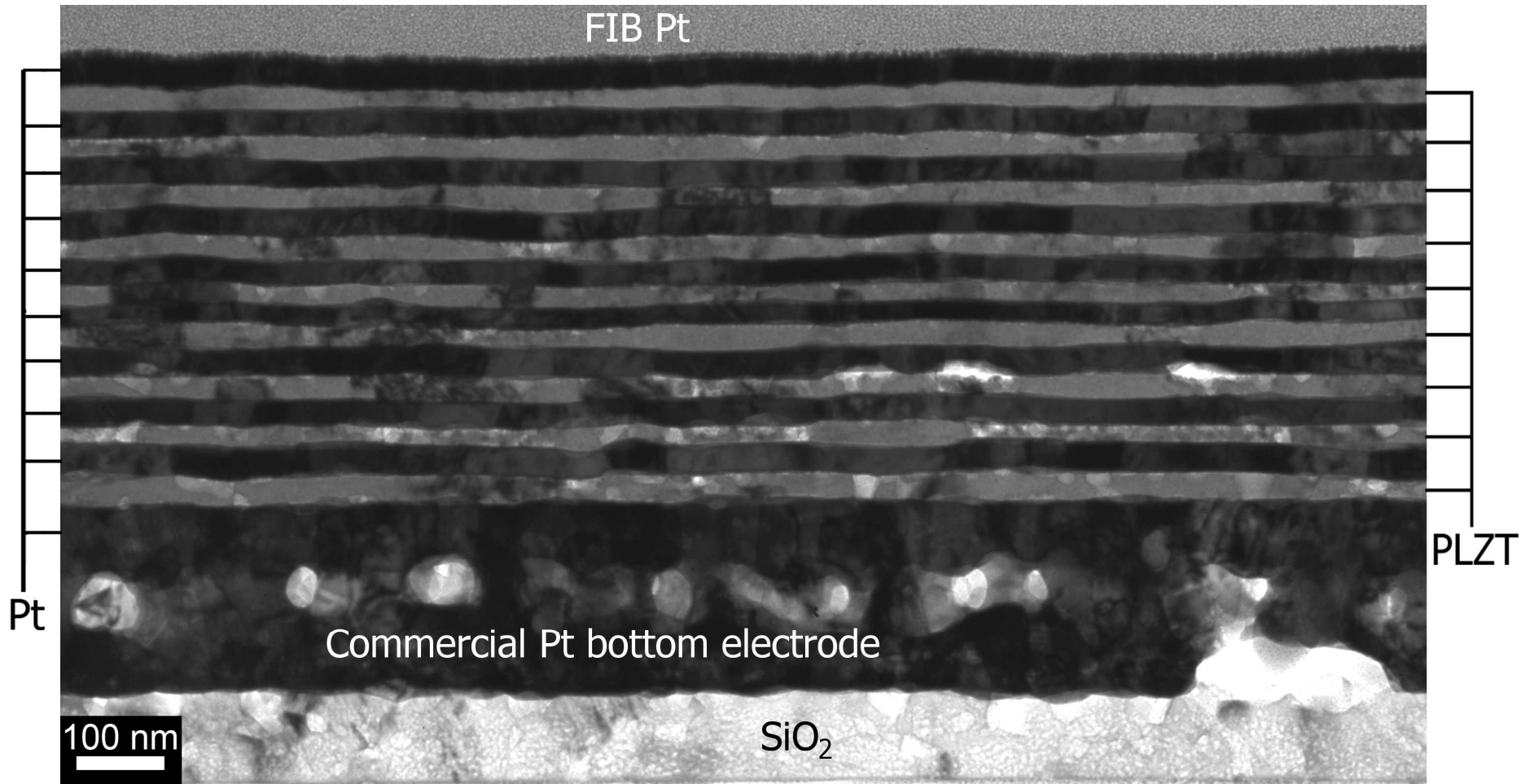


Photo-resist masked wet etch enables connections between alternate layers

Brennecka, et al., *J. Mater. Res.* (2008)

Multilayer Structures

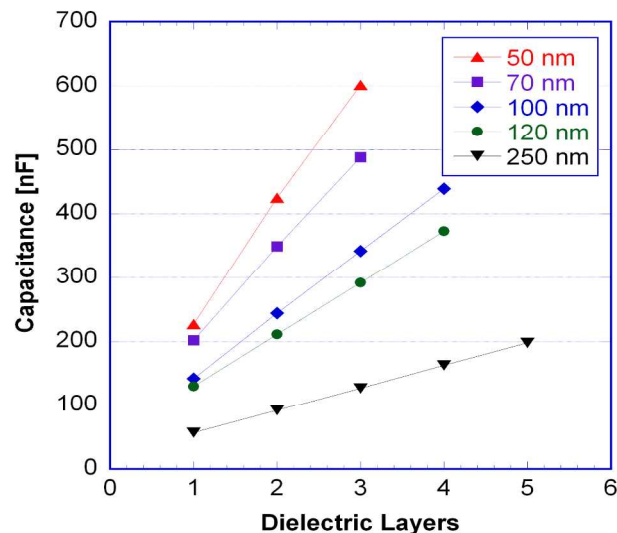


9 layer capacitor structure with ~20nm solution-deposited PLZT layers and ~20nm sputtered Pt electrodes

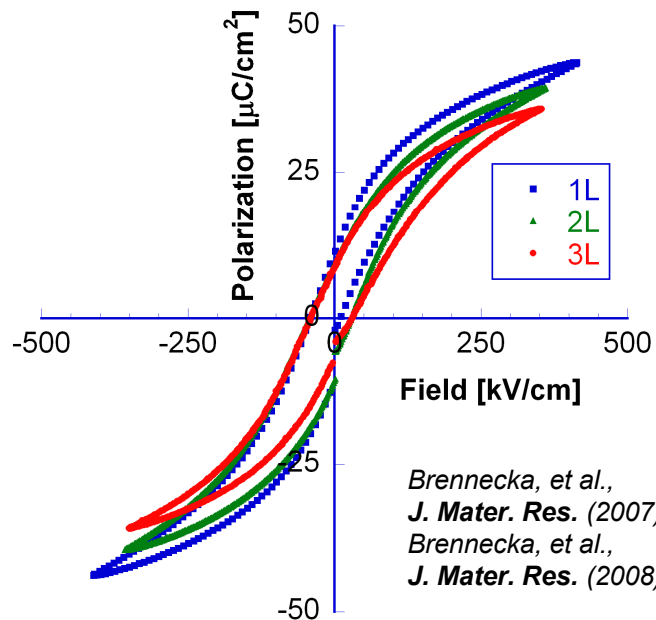
Brennecka, et al., J. Mater. Res. (2008)



Electrical Performance

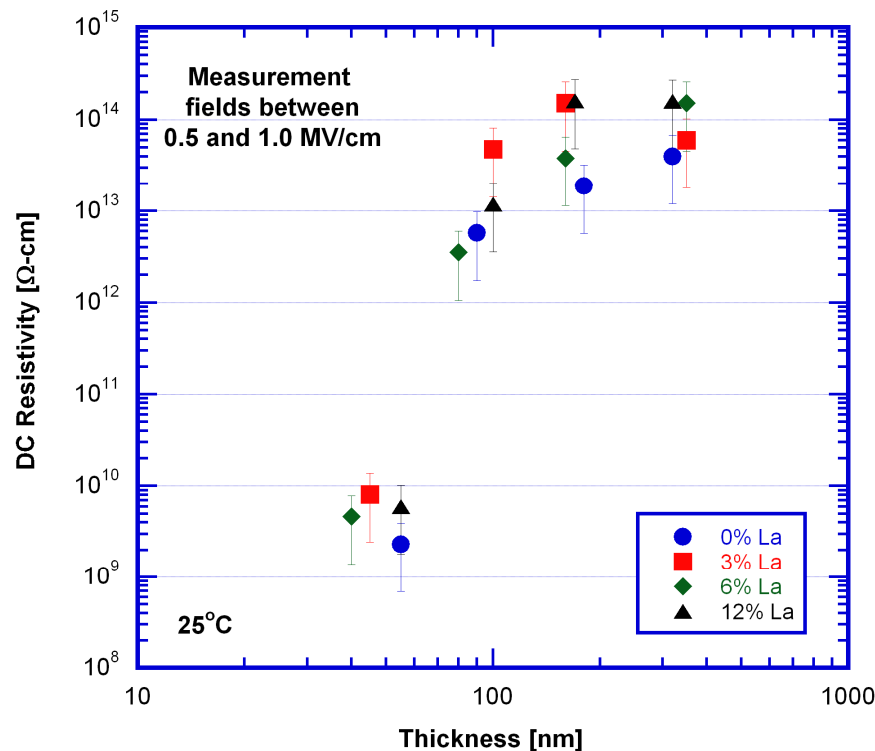
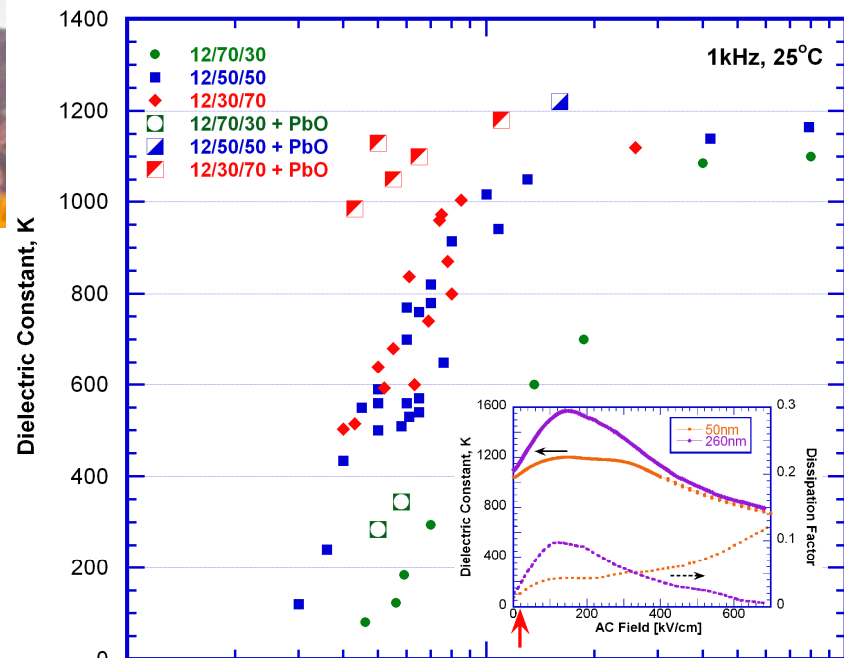


Good news:
Properties scale well with number of layers

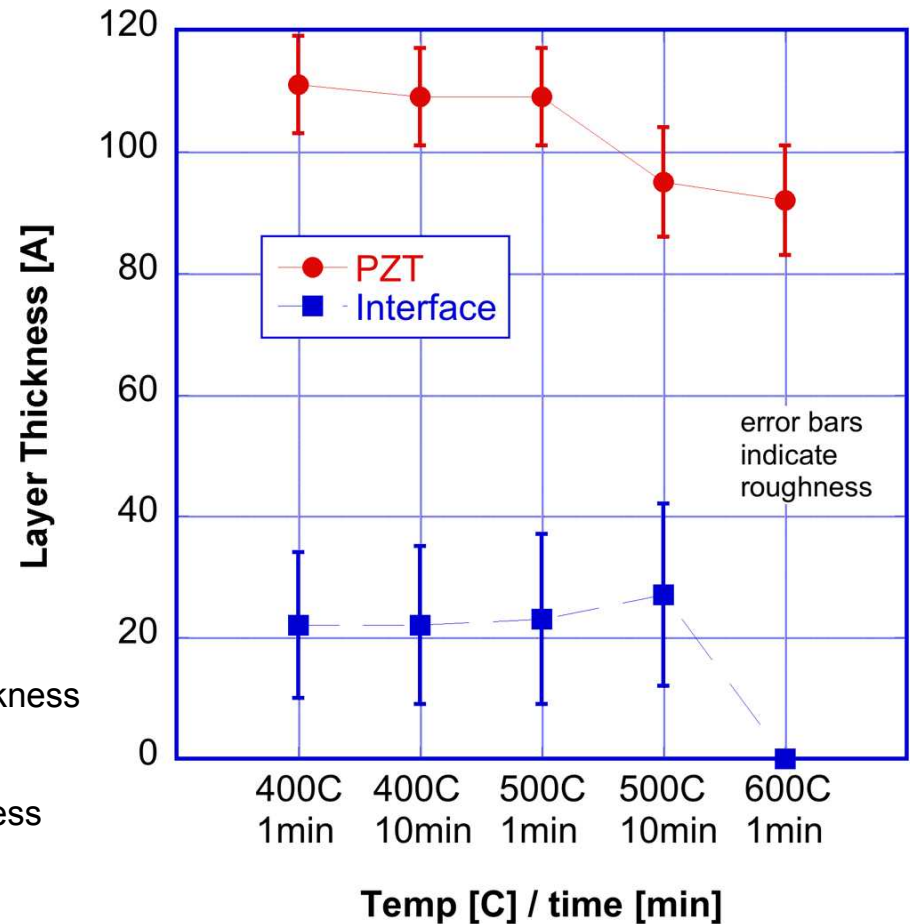
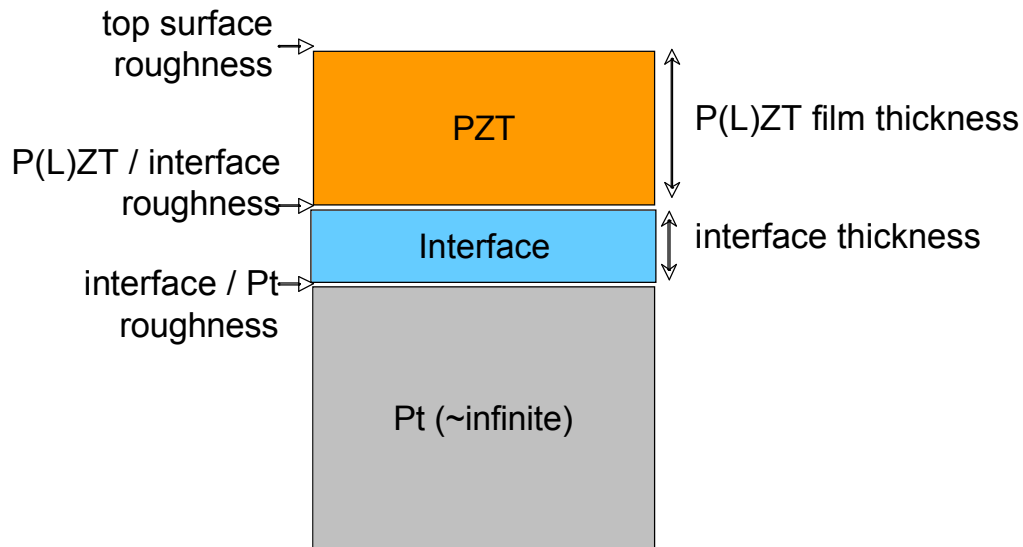
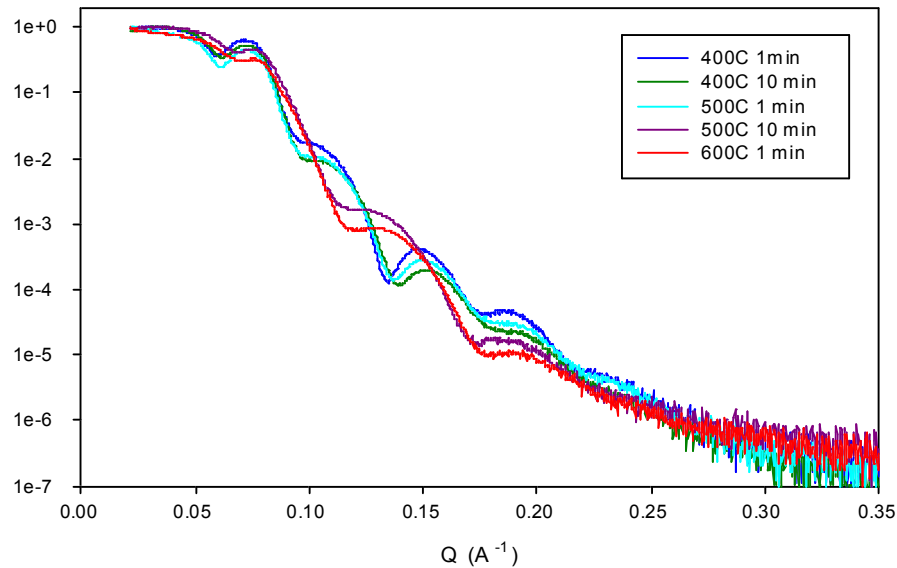


*Brennecke, et al.,
J. Mater. Res. (2007)
Brennecke, et al.,
J. Mater. Res. (2008)*

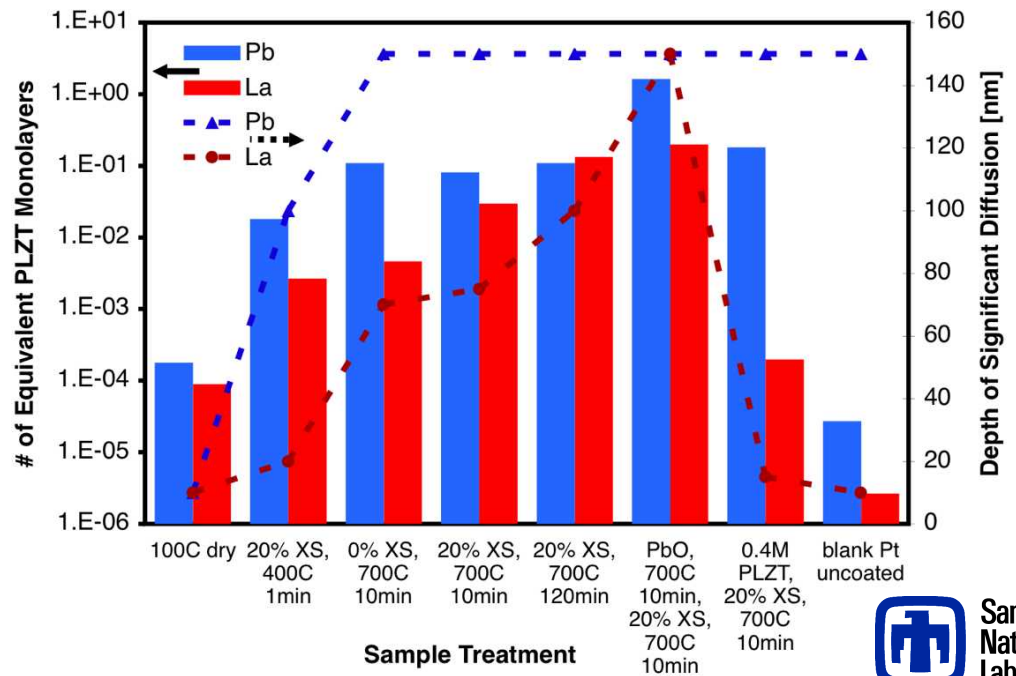
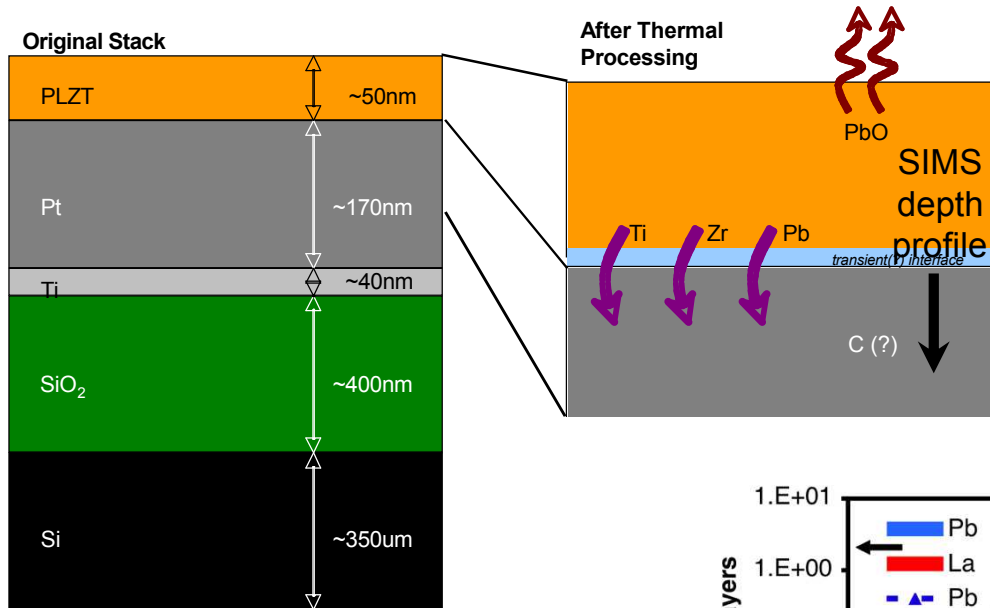
Bad news:
Properties are severely compromised below ~50nm



PLZT-Pt Interactions

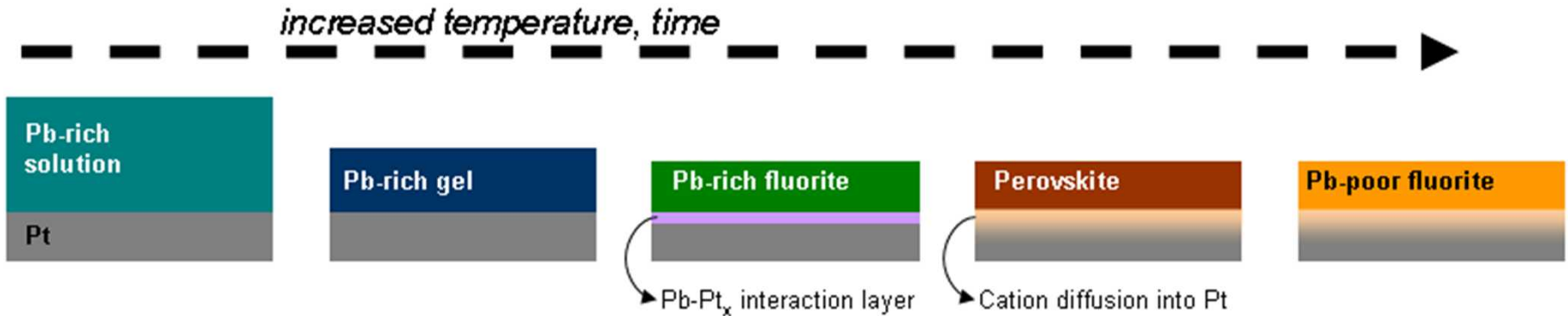


PLZT-Pt Interactions



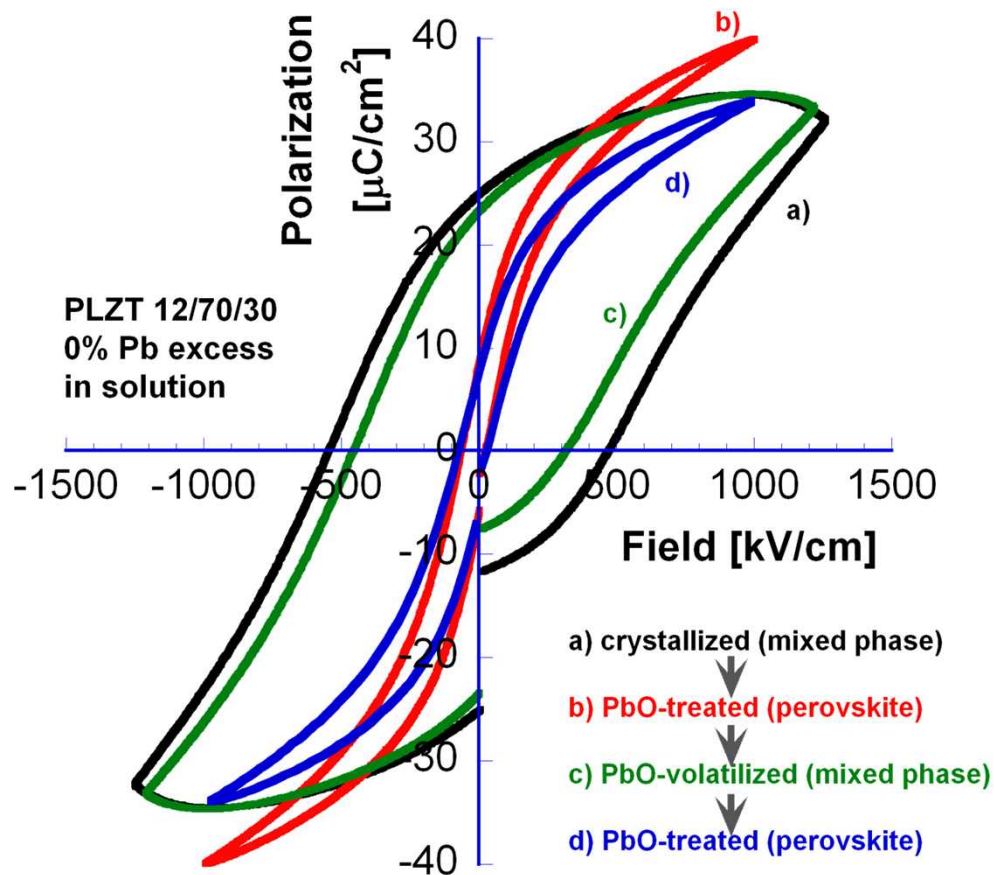
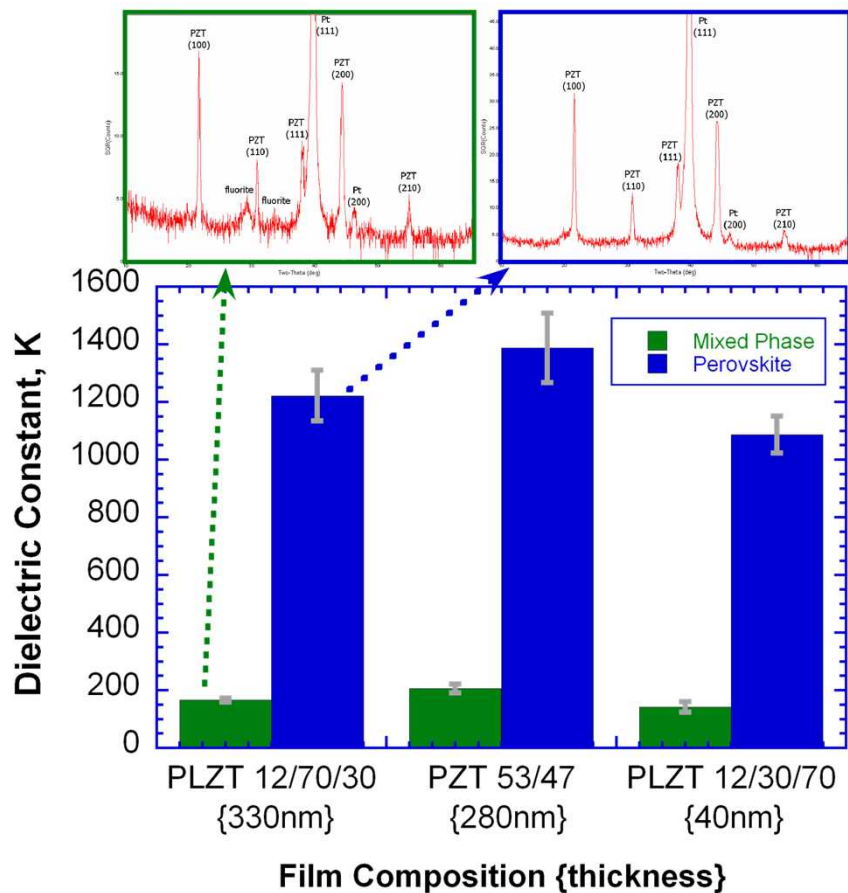
Fluorite $\Leftrightarrow$ Perovskite Reversibility

Traditional processing

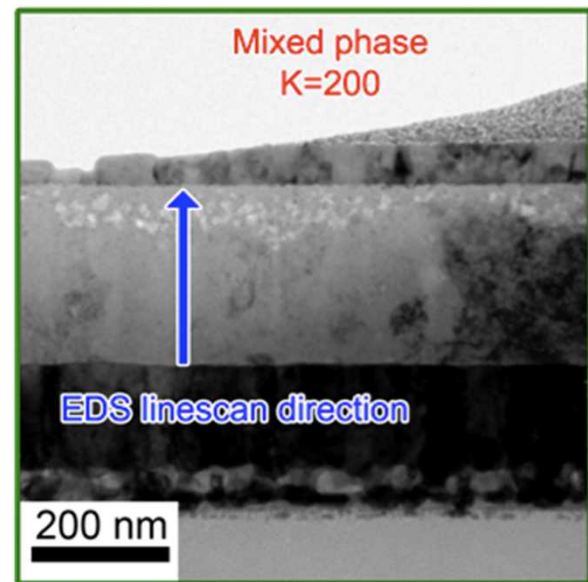


Pb-deficient followed by conversion

Fluorite $\Leftrightarrow$ Perovskite Reversibility



Fluorite $\Leftrightarrow$ Perovskite Reversibility



FIB Pt

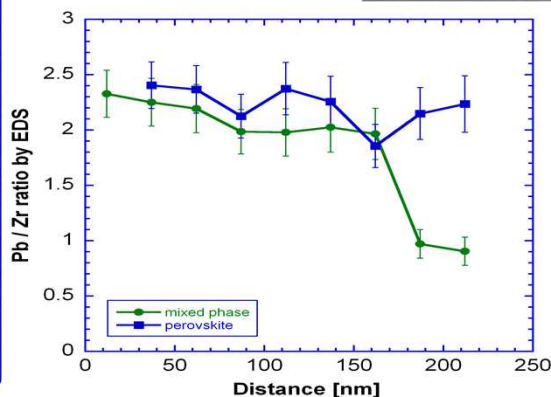
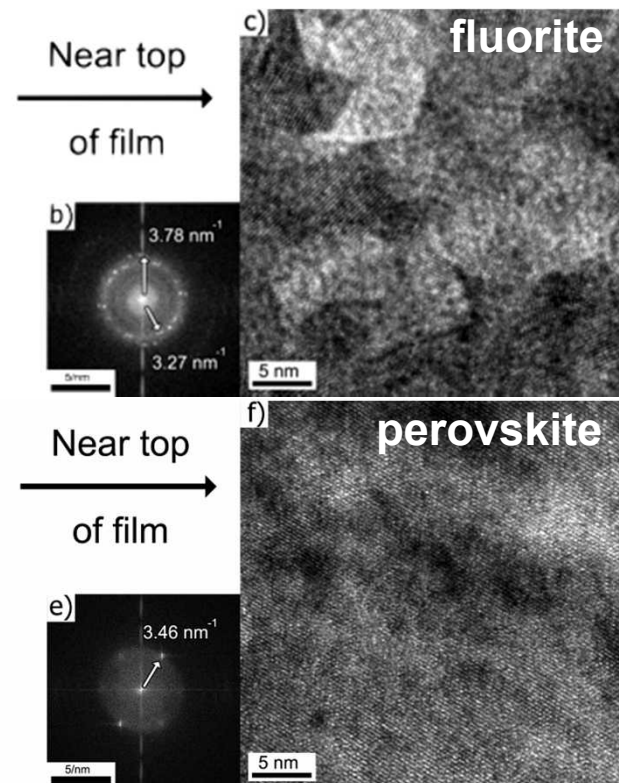
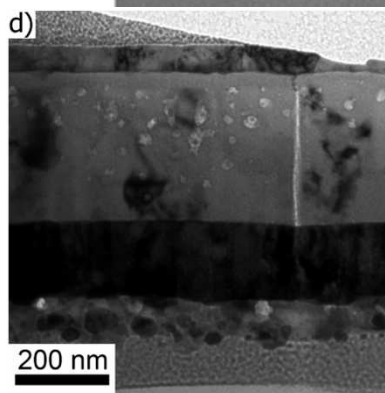
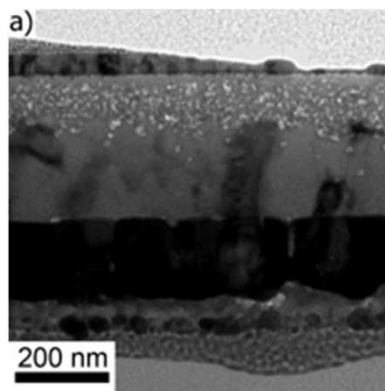
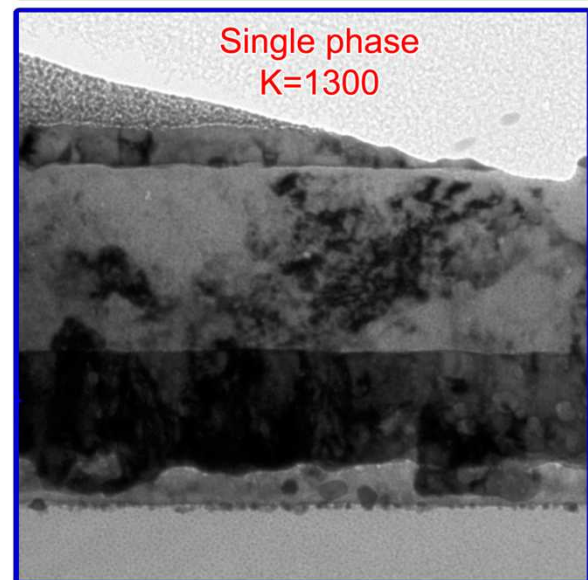
Pt

PZT

Pt

TiO_x

SiO₂

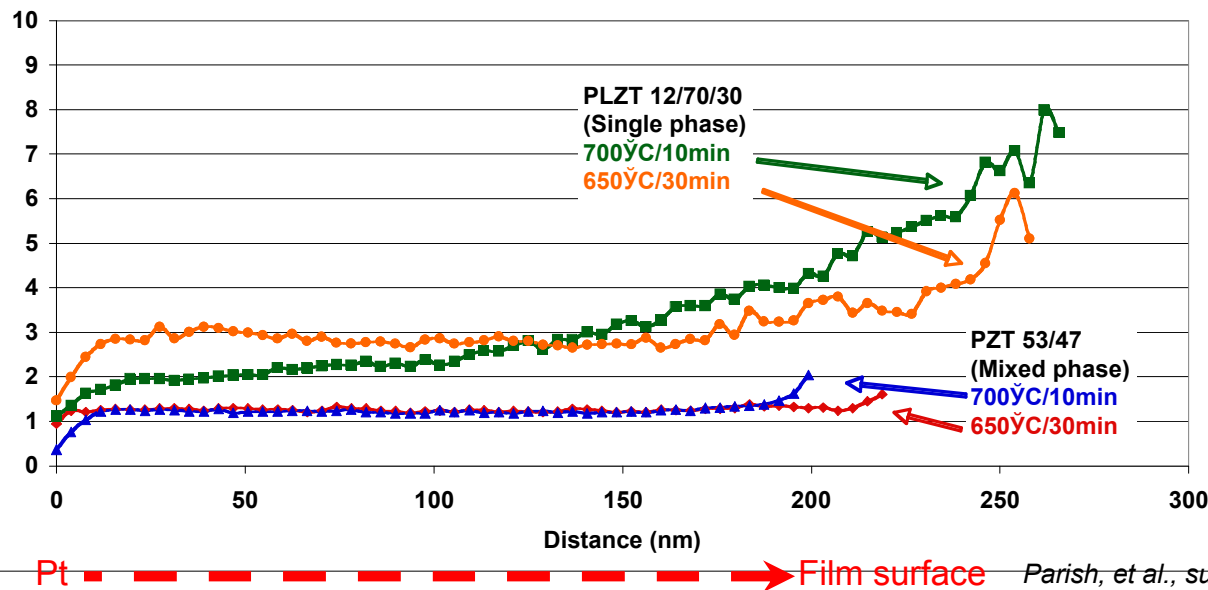
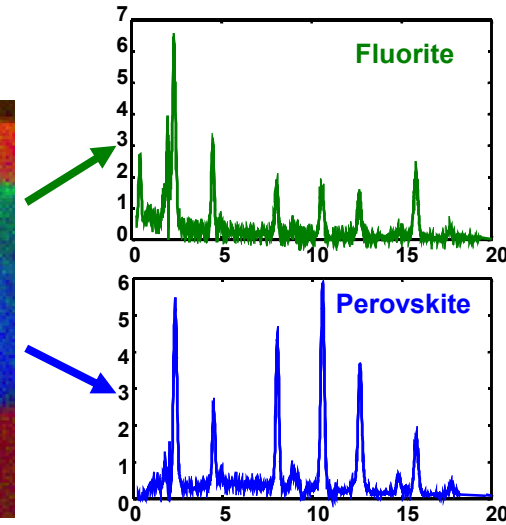
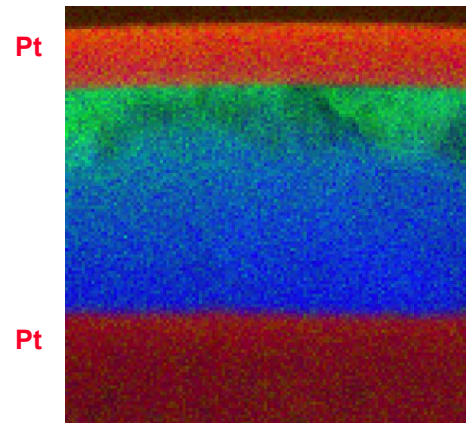
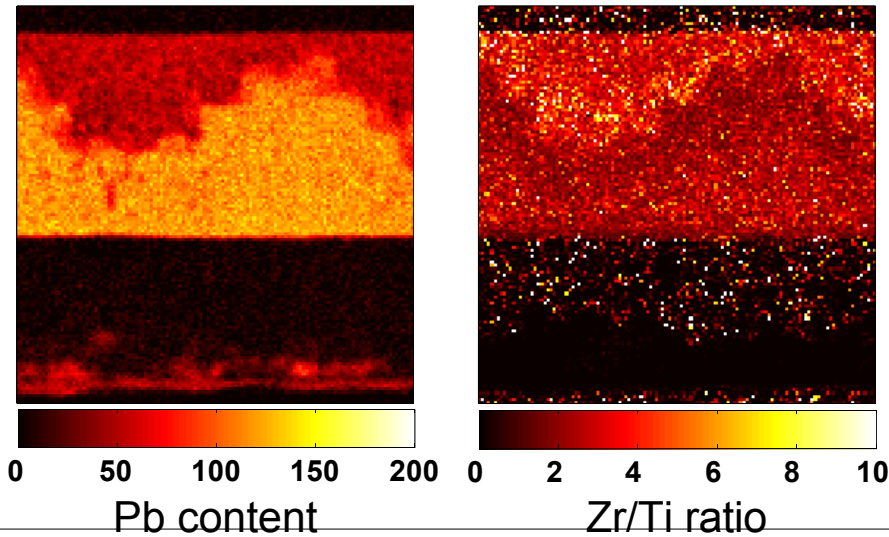


PLZT 12/70/30
0% Pb excess
in solution

PZT 53/47
10% Pb-deficient
solution

Brennecke, et al.,
Adv. Mater. (2008)

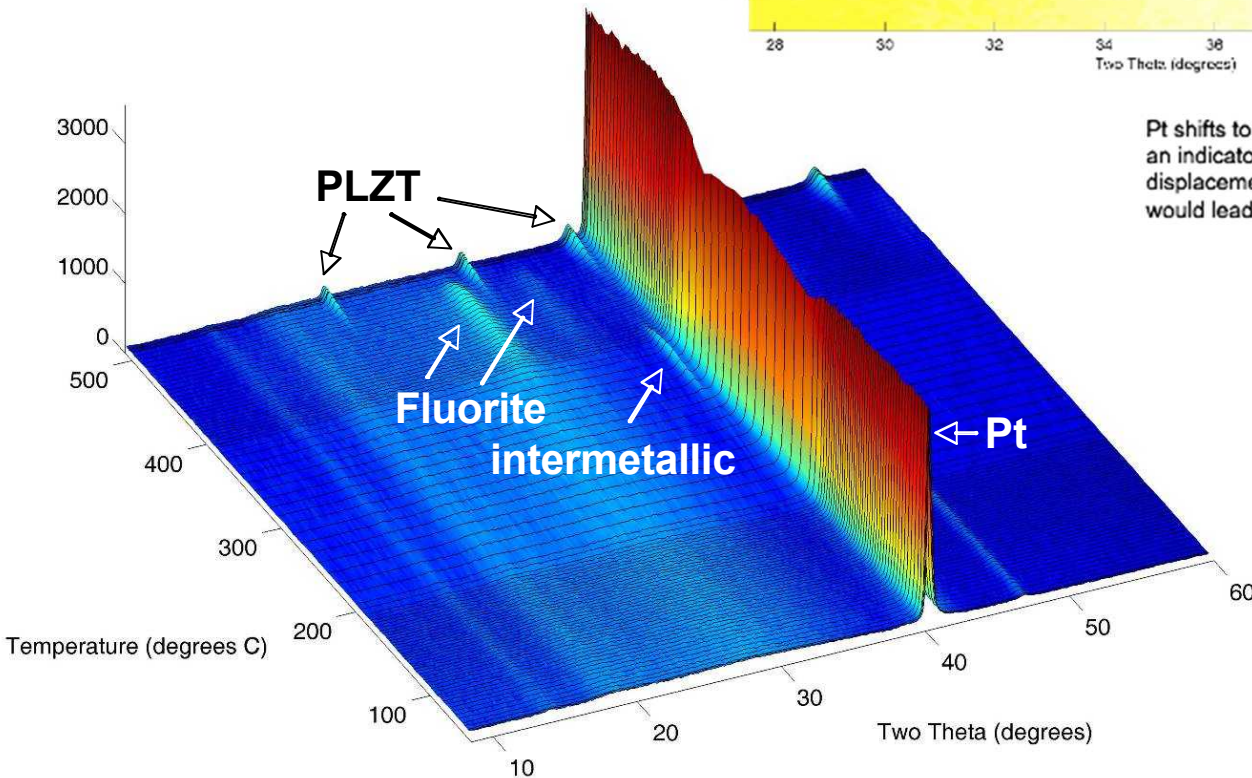
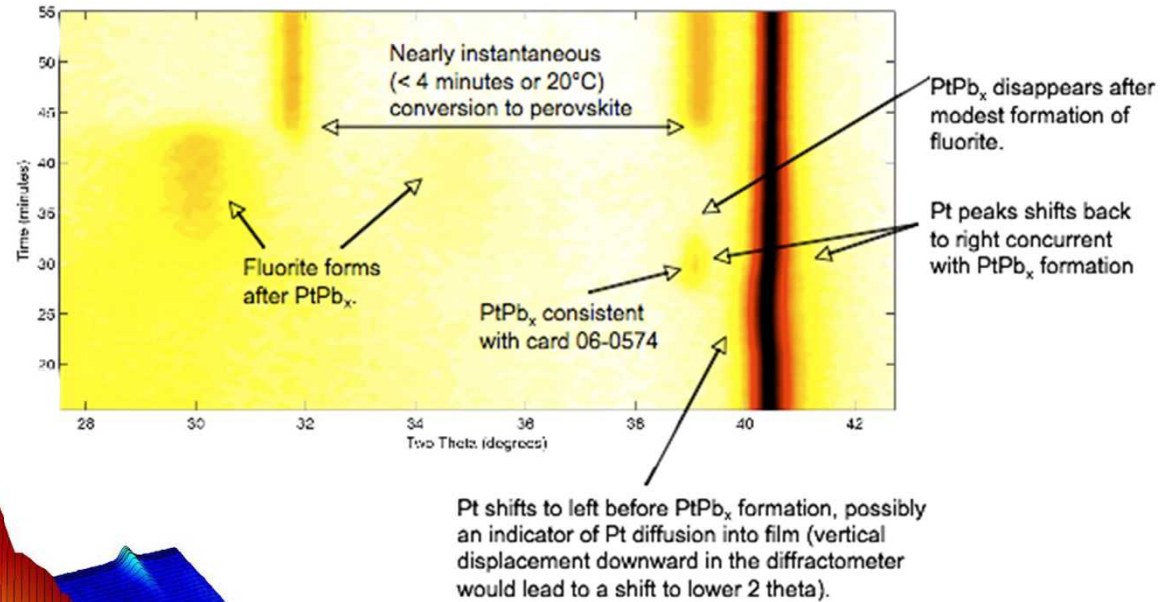
Quantitative Cation Mapping



Multivariate statistical analysis of TEM EDS data allows single-pixel resolution chemical and/or phase determination

in-situ X-Ray Diffraction

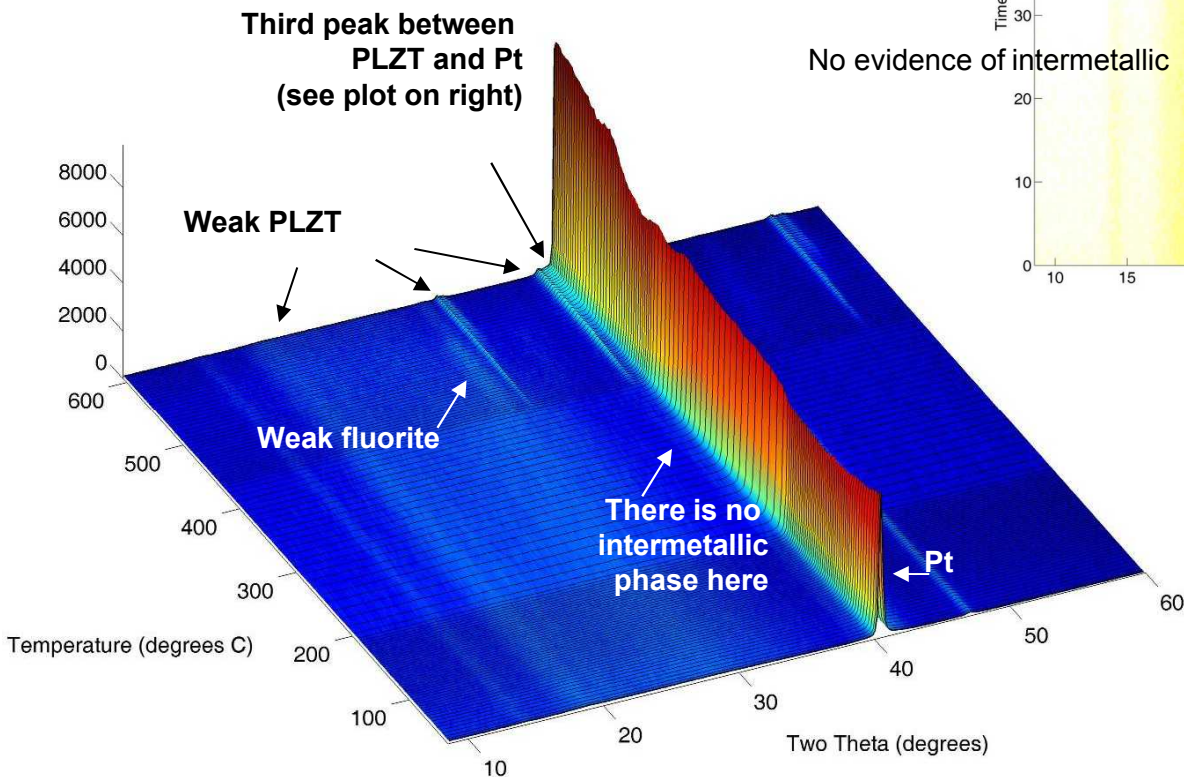
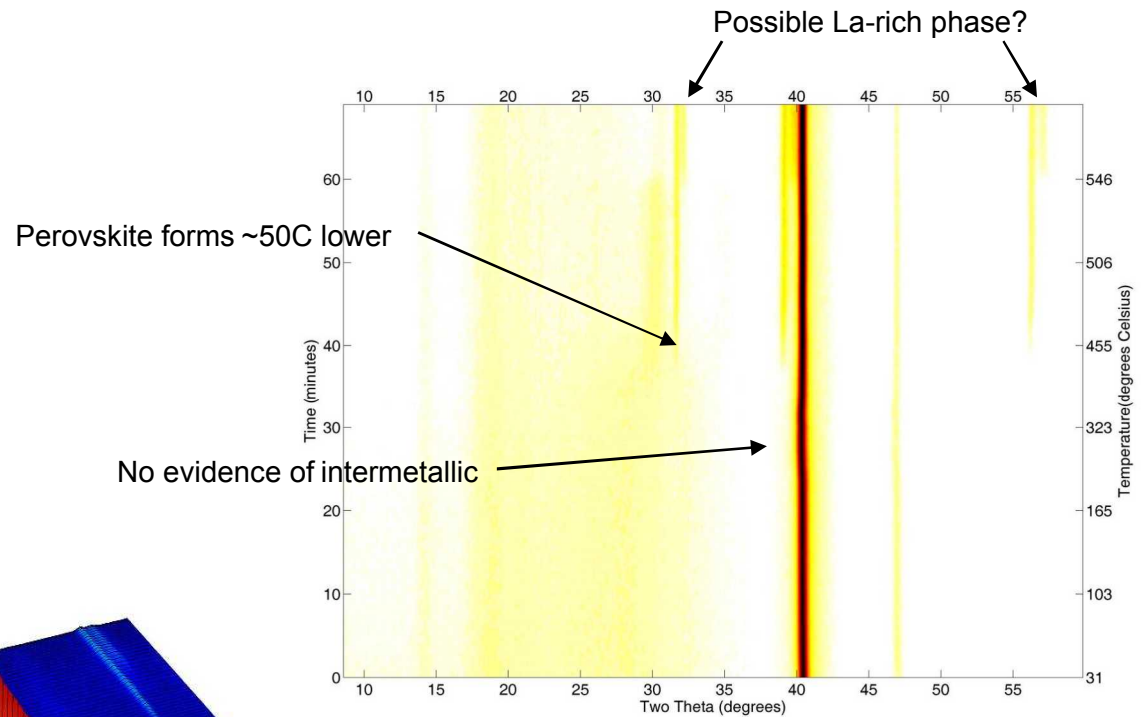
Crystallization of PLZT thin film from a solution containing 20% XS Pb



*in collaboration with
Jacob Jones at the
University of Florida*

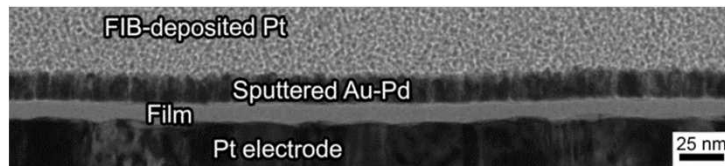
in-situ X-Ray Diffraction

Crystallization of PLZT thin film from a solution containing 20% Pb deficiency



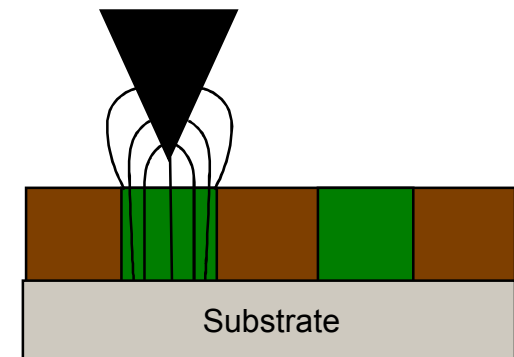
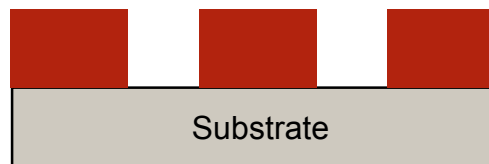
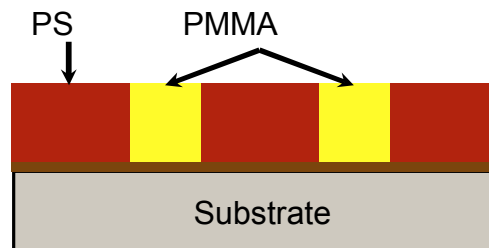
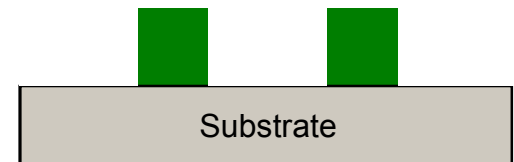
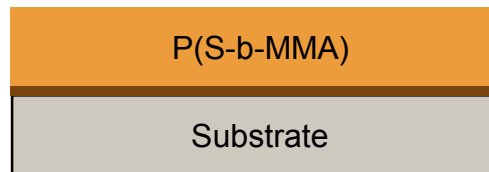
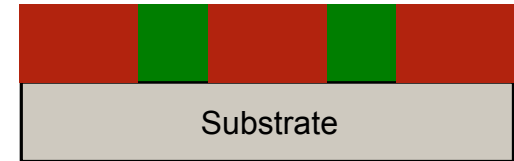
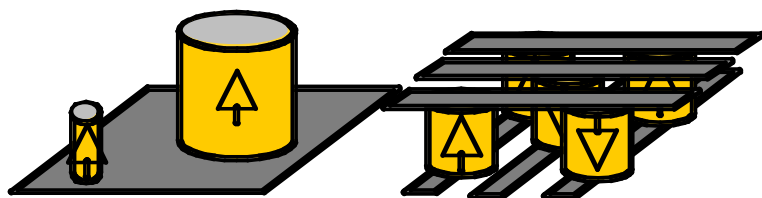
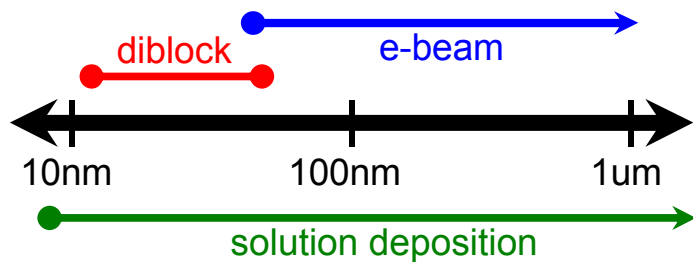
*in collaboration with
Jacob Jones at the
University of Florida*

Extend Ultrathin Films into 2D Patterning



Generic platform for nanoscale studies and device fabrication

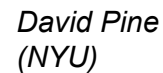
- continuous dimension control
- **variety of materials systems**
- studies of fundamental size, aspect ratio, and interface effects



Working with UT-A and UWisc on surface treatment and diblock orientation



Diblock Copolymer Self-Assembly



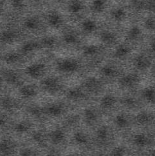
- PMMA cylinders
perpendicular to
surface



Insulator



Insulator

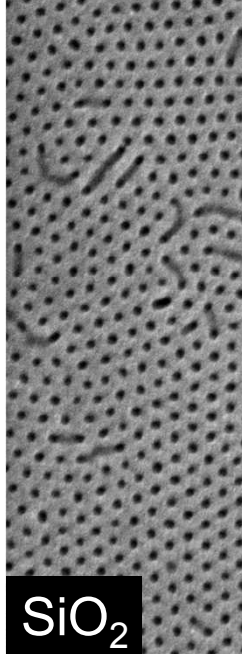
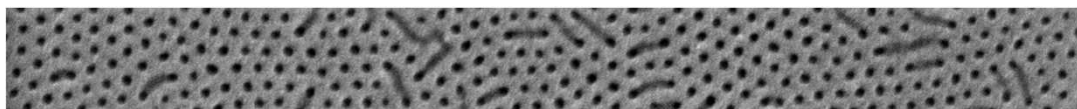


100 nm

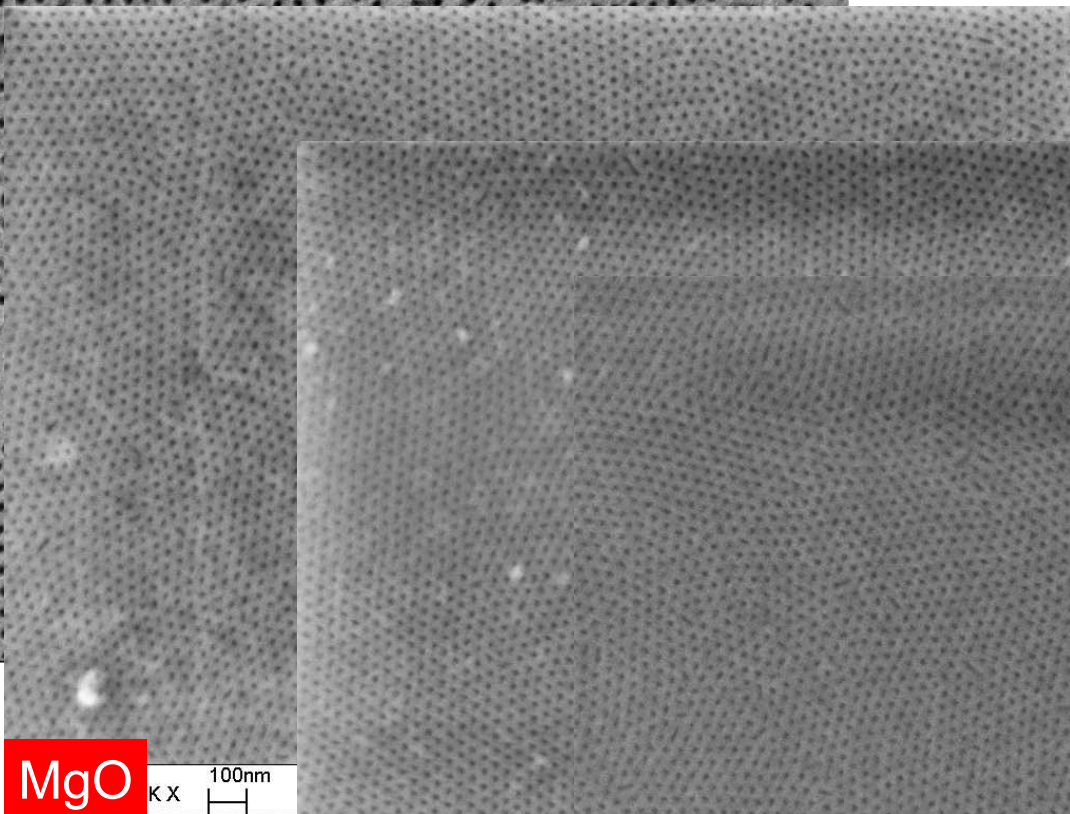
- Mn = 78000 g/mol
- 83% styrene
- 17% methyl methacrylate
- 12 nm diam pores
- $\sim 1.2 \times 10^{11} \text{ cm}^{-2}$

Assembly done at UT-A

Diblock Patterning on Various Substrates

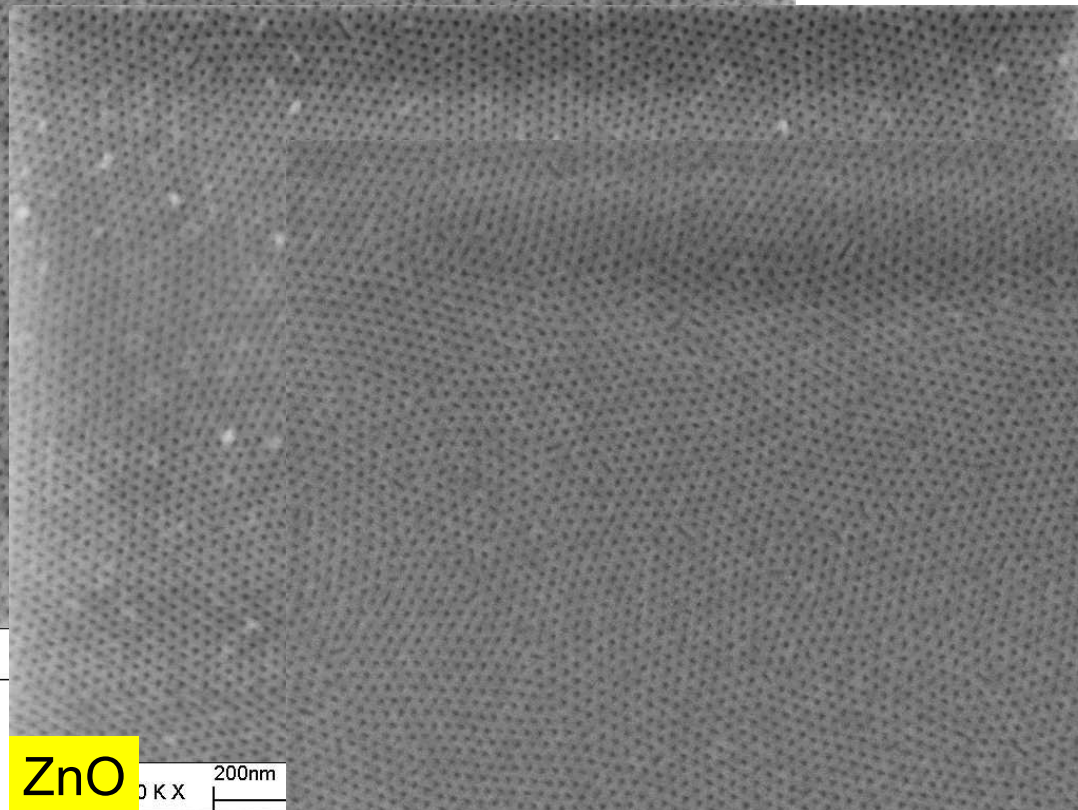


SiO_2



MgO

K X 100nm



ZnO

K X 200nm



ZrB_2

K X 100nm

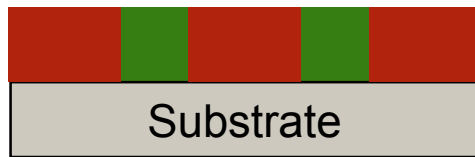
EHT = 1.00 kV
WD = 4 mm

Signal A = InLens
Photo No. = 8920

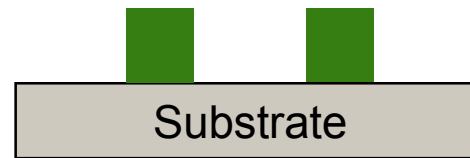
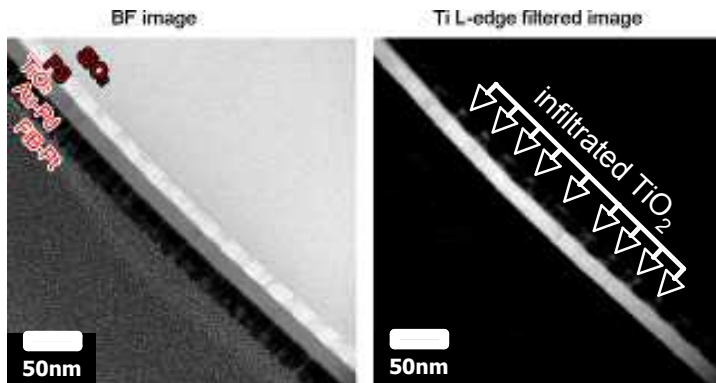
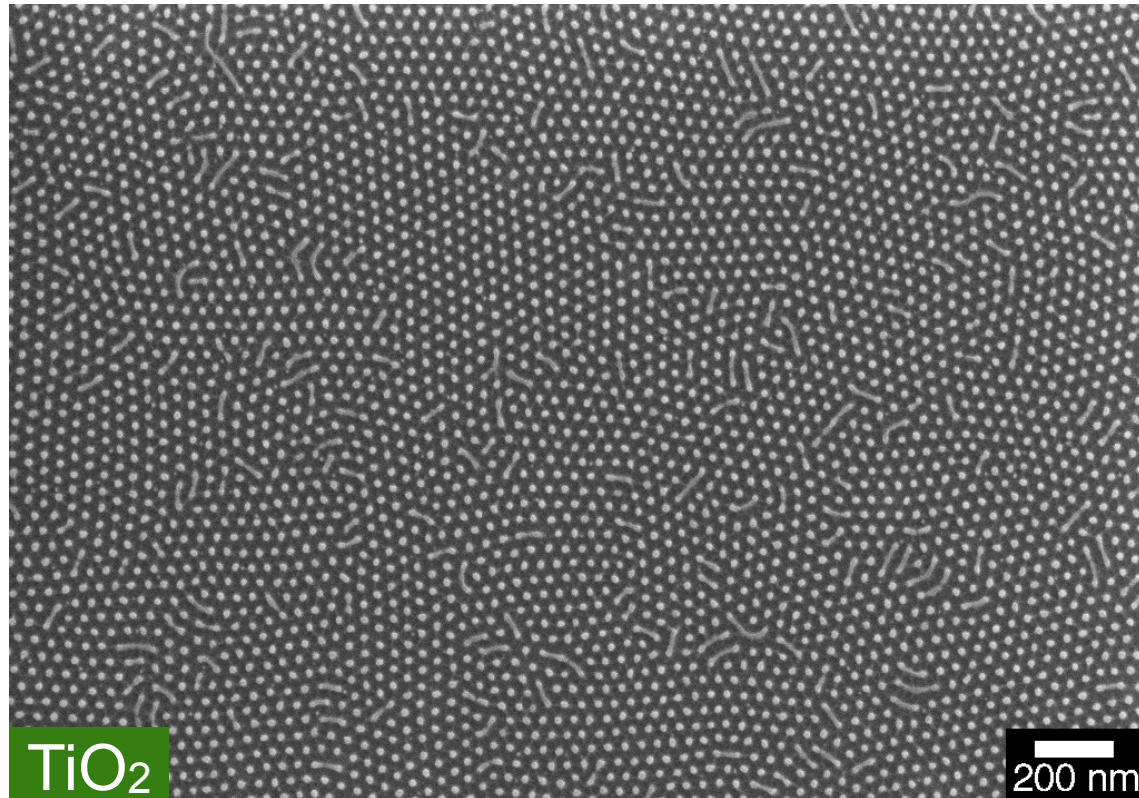
Date :24 Jul 2008
Time :19:26:28 G.Liu

Assembly done at UT-A and/or UWisc

Deposition of Electronic Oxides



Gel

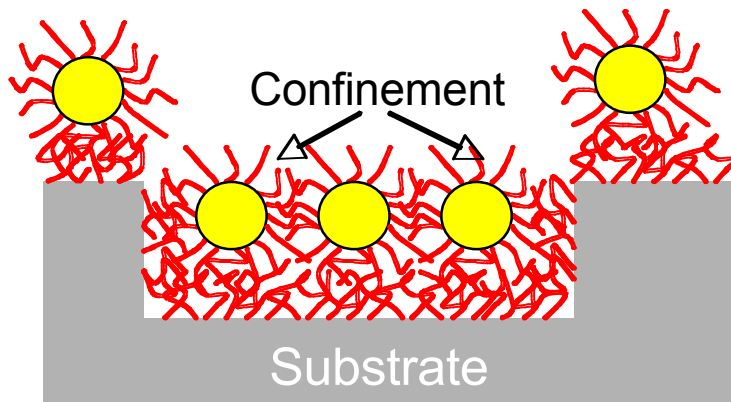


Remove PS

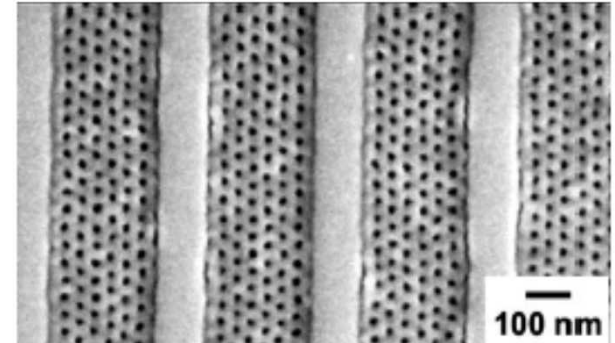
*Technique also shown
to be compatible with
Ni, V, and Mn oxides*

Graphoepitaxy

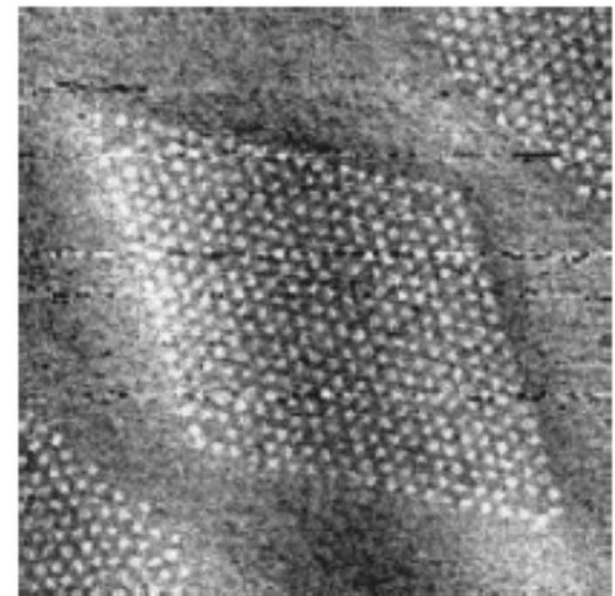
- Geometric confinement can lead to 'crystalline' single-domain state
- Demonstrated for Si / SiO₂ with cylindrical and spherical diblocks
- *Pre-defined pixel location*



R.A. Segalman, et al., *Macromolecules*, 36 4498-4506 (2003)

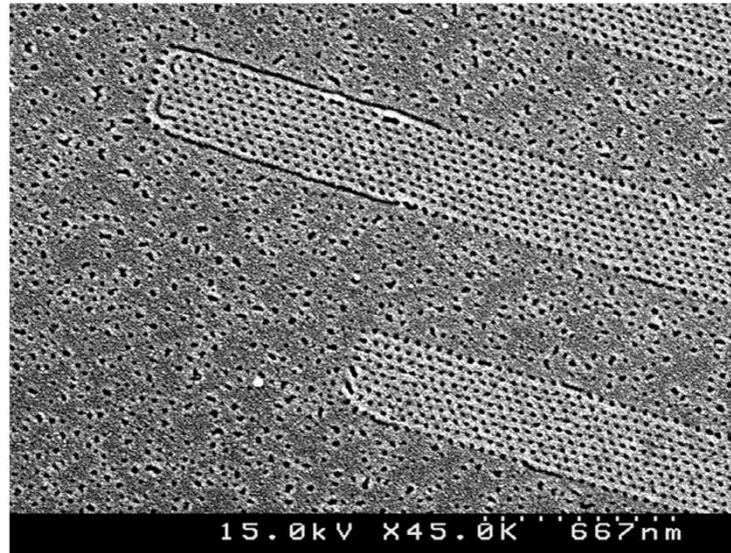
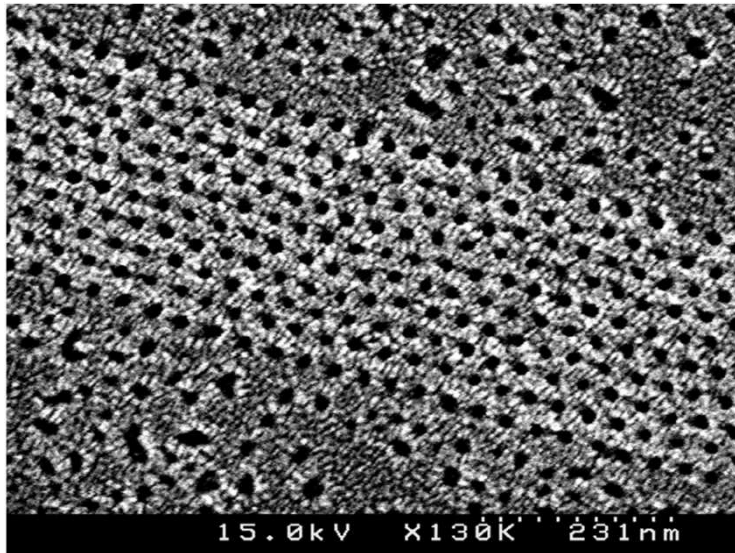


C. T. Black, et al., *IEEE Trans. Nanotechnology* 3 (5) 412-415 (2004)

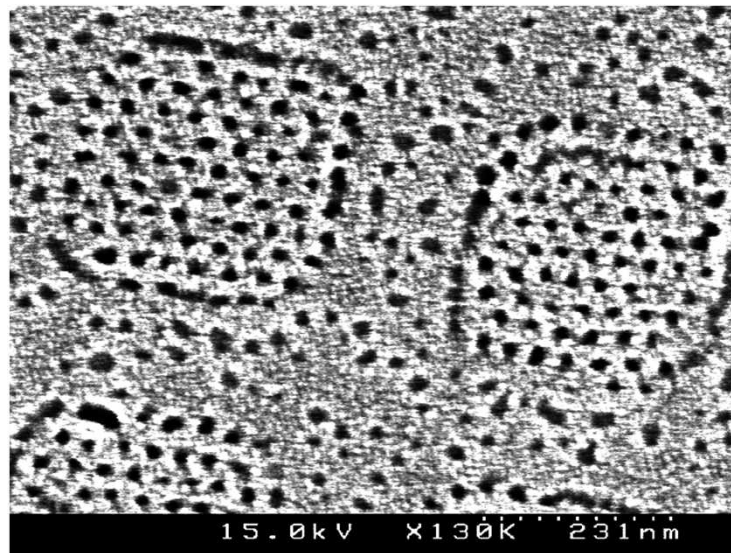
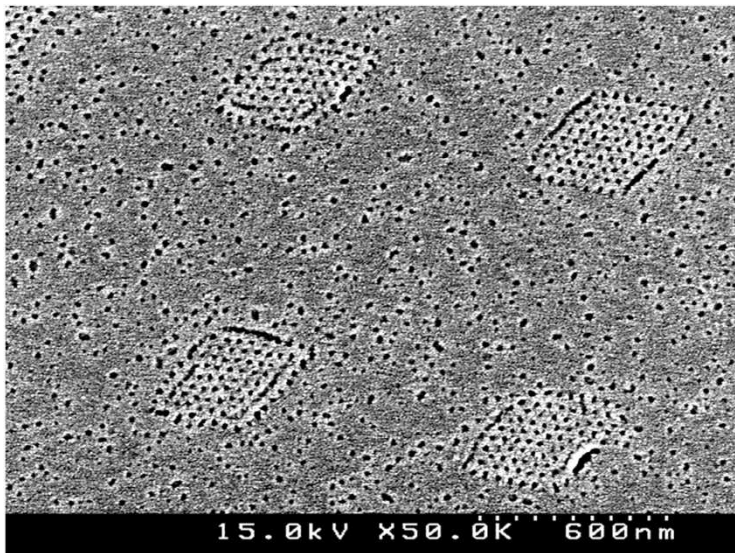


Kimura, et al., *MRS Symp. Proc.* 901E, 0901-Ra05-05-Rb05-05.1 (2006)

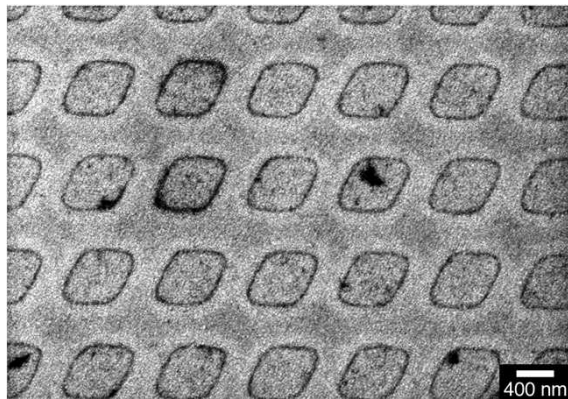
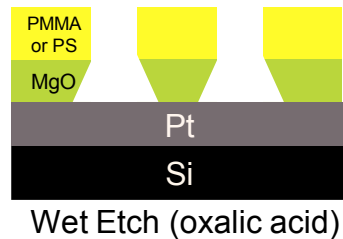
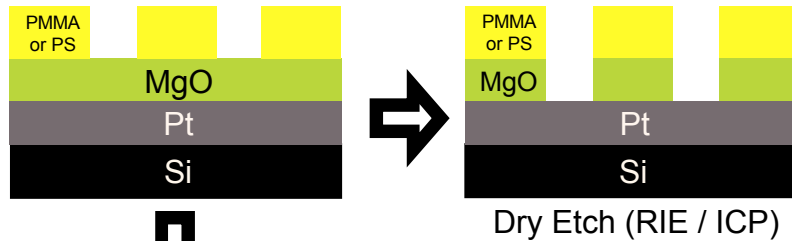
Successful Graphoepitaxy (UT-A)



*(250nm wide
features, 35nm
thick diblock
copolymer)*



Pattern Transfer for Added Flexibility



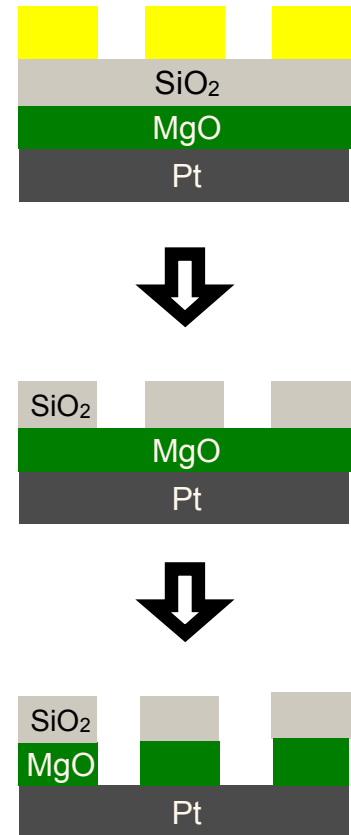
Wet etch:

- high selectivity
- low edge resolution



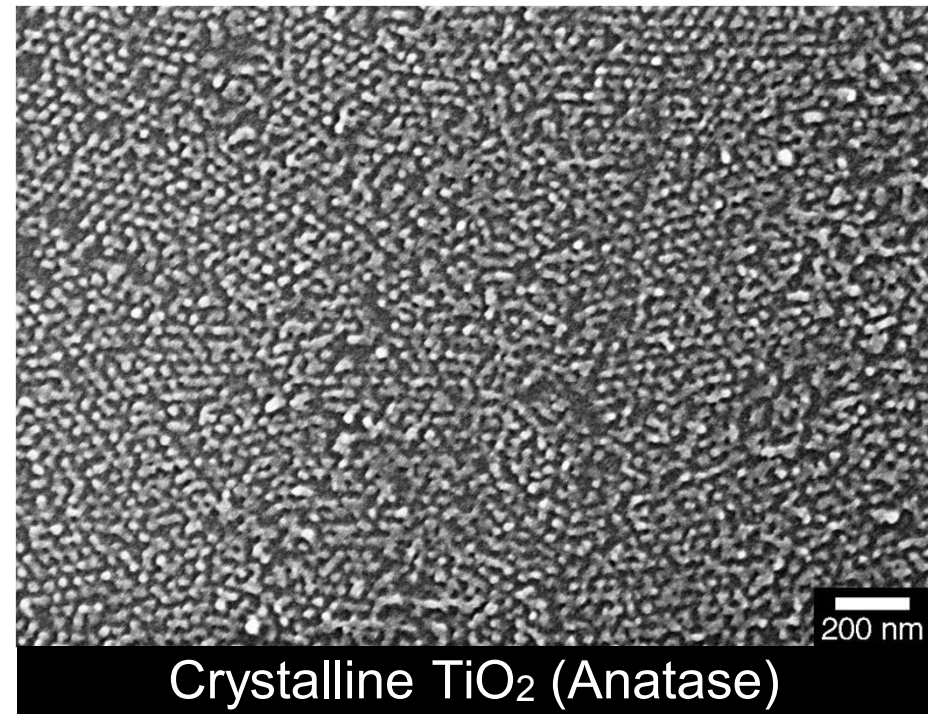
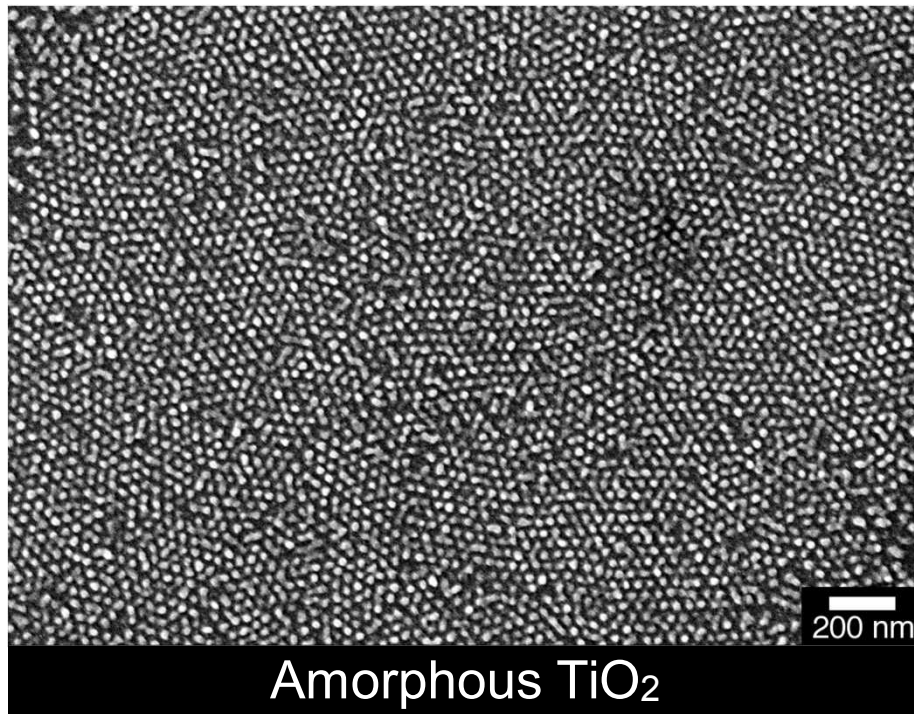
Dry etch:

- low selectivity
- relatively high edge resolution
- attempting SiO₂ hard mask



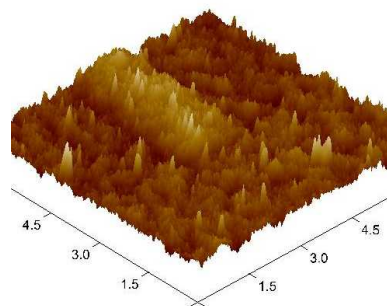
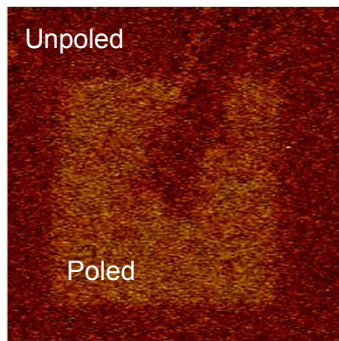
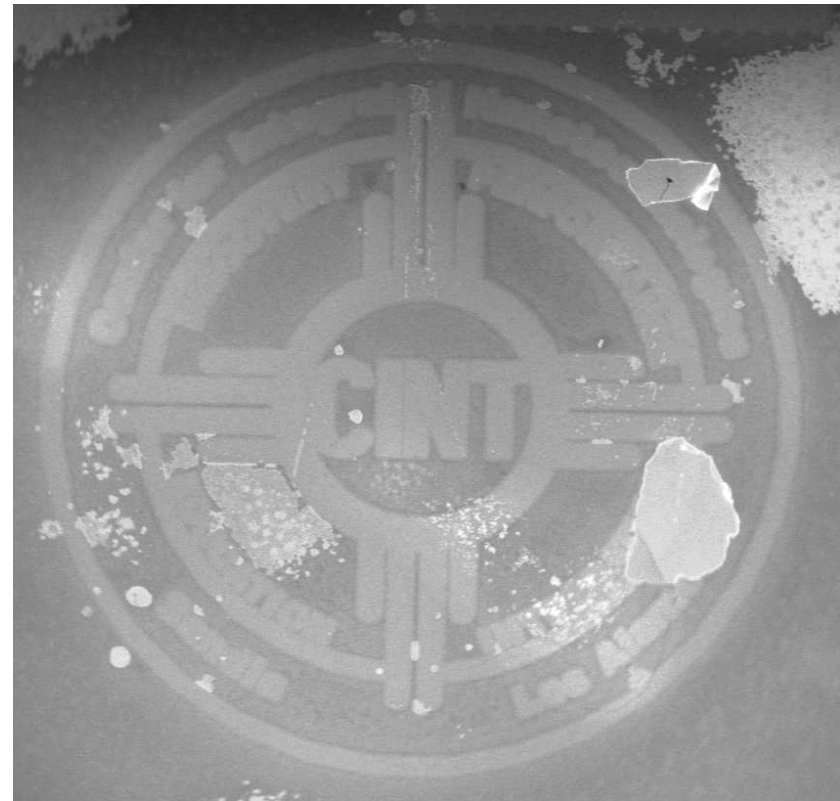
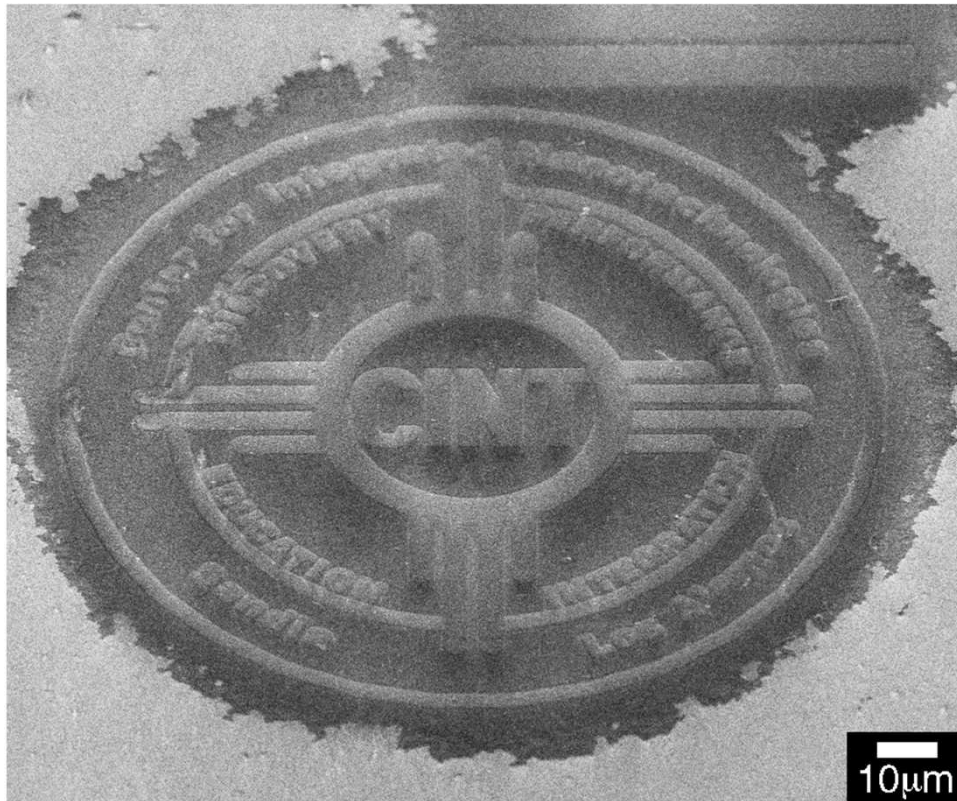
Crystallization of Freestanding Nanofeatures

After removal of PS mask, TiO_2 nanopillars were heated to 550°C for 30min to crystallize.



Nanofeatures are still mostly discrete, but some ripening has taken place.

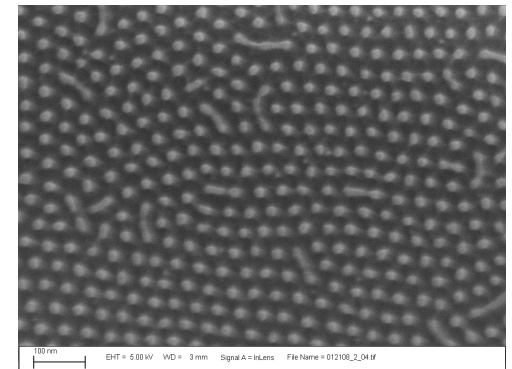
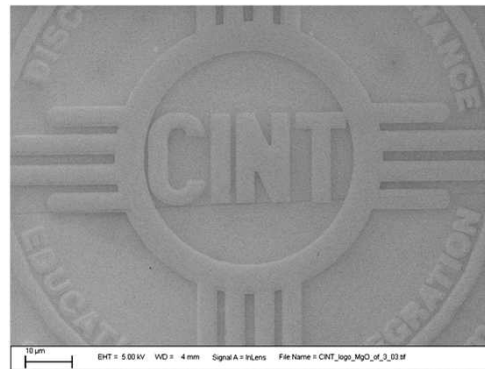
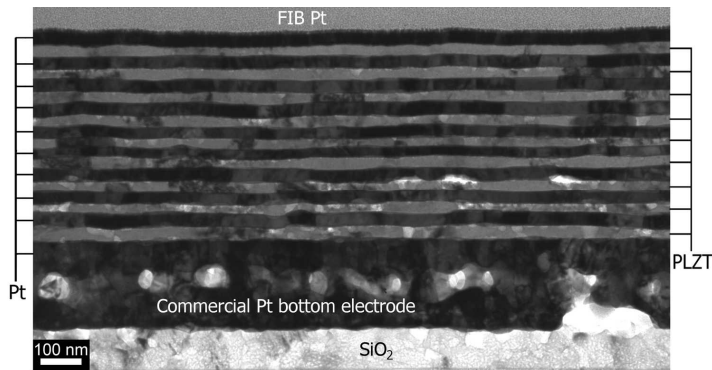
MgO-Mediated Pattern Transfer to PZT



- Pattern transfer (top left)
- Pt liftoff (top right)
- PZT is piezoelectric and appears to be ferroelectric

Summary

- Continuous single or multilayer films for capacitor applications
 - Optimization of film performance below ~50nm requires better control of phase / interface development



- General patterning approach
 - Useful platform for fundamental studies and devices
 - Diblock-copolymer mask for ~12-50nm feature definition
 - Graphoepitaxy (and/or chemical patterning) for bi-level pattern control
 - Etching step currently the limiting factor for breadth of materials capabilities